

STAR Forward GEM Tracking Upgrade

Physics Motivation

Design

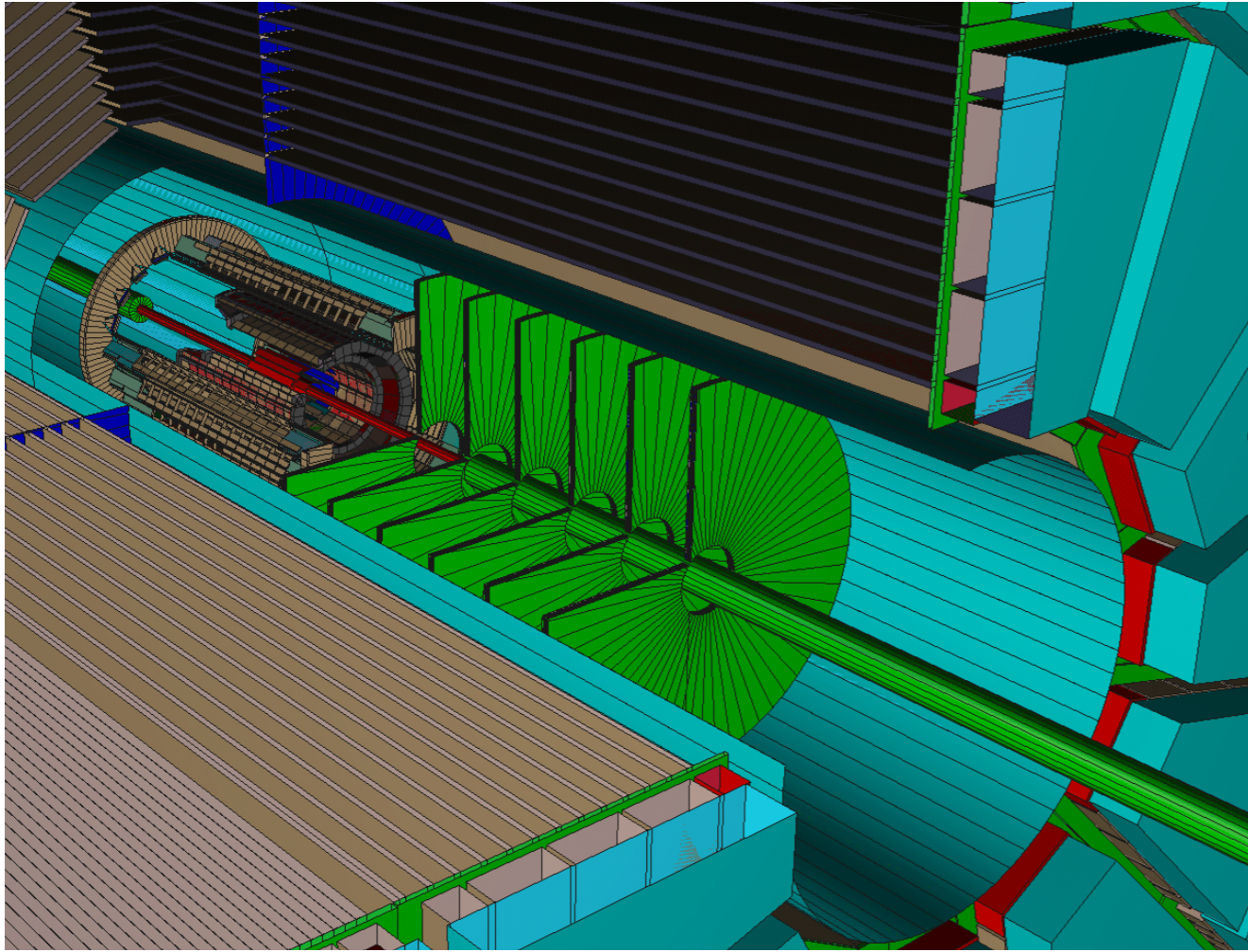
GEM Foils

2D Readout

APV Boards

Packaging APV Chips

RHIC Spin at STAR



500 GeV RHIC spin program

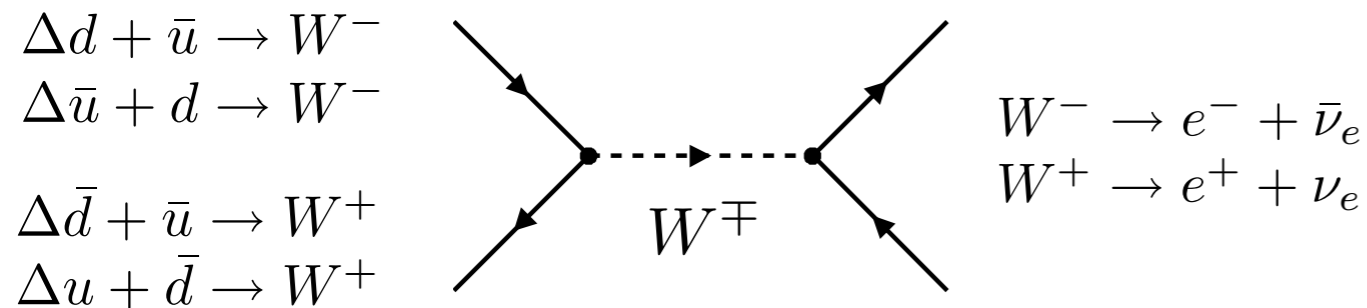
- flavour spin structure of proton
- tag $W^\pm \Rightarrow e^\pm$
- identify e^\pm from curvature at forward angles
 - sagitta ~ 1 mm

High rate environment

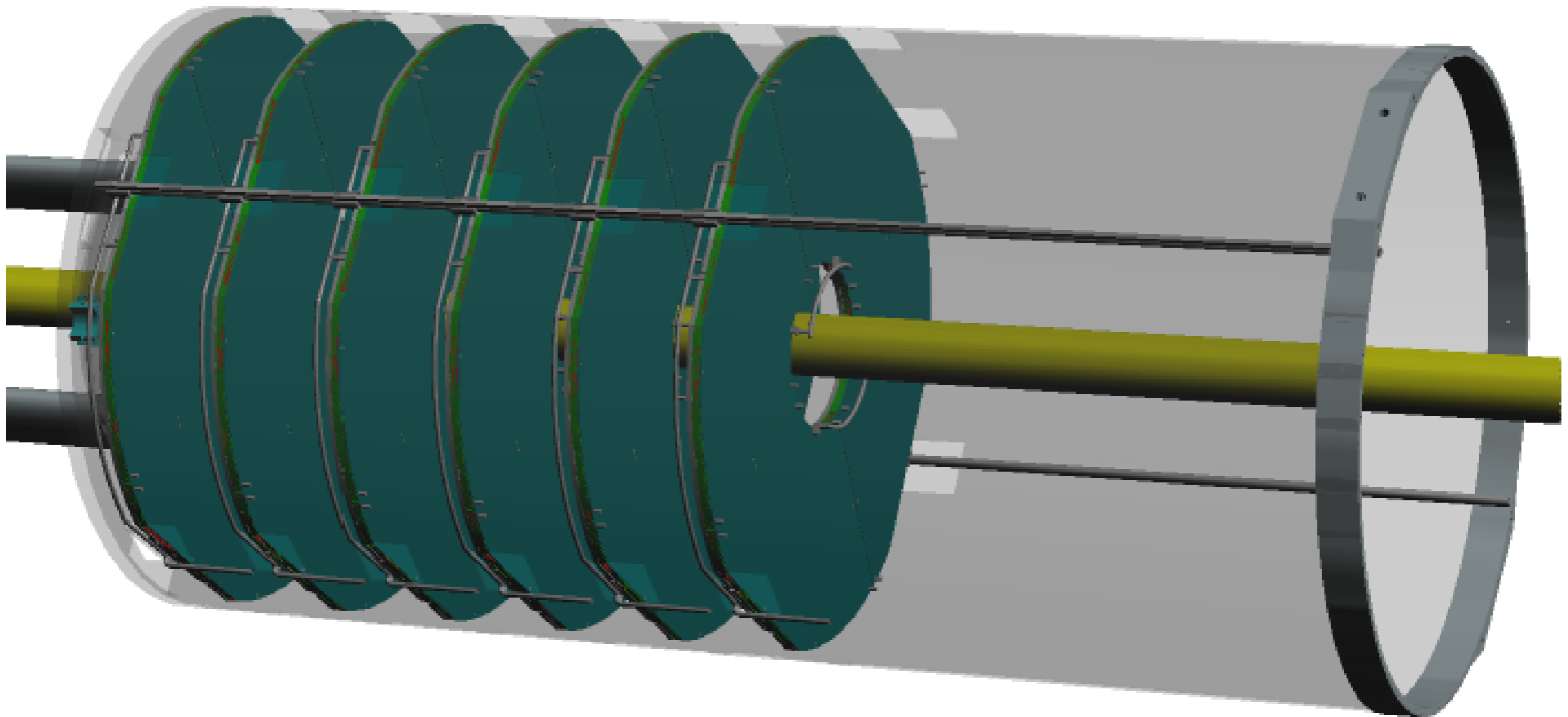
- beam crossing 107 ns
- minimise material

Choose GEM detectors

- 6 disks of triple GEM detectors
- active area $R = 11.5 - 38.25$ cm
- < 100 micron resolution
- $\sim 0.67\%$ X_0



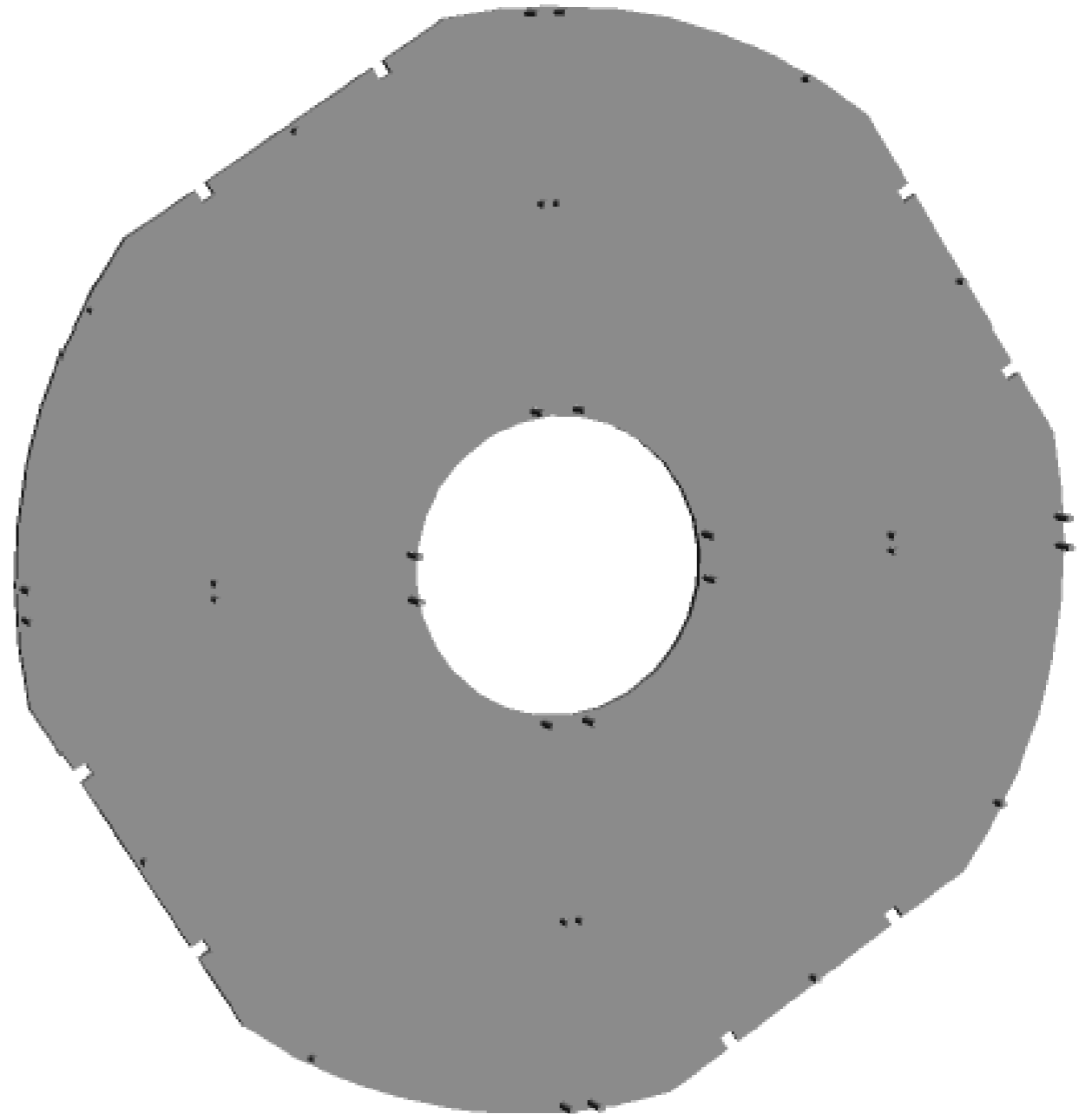
FGT Disks in West Support Cylinder



FGT Disk Concept

Nomex disk

- 5 mm thick honeycomb
- alignment pins



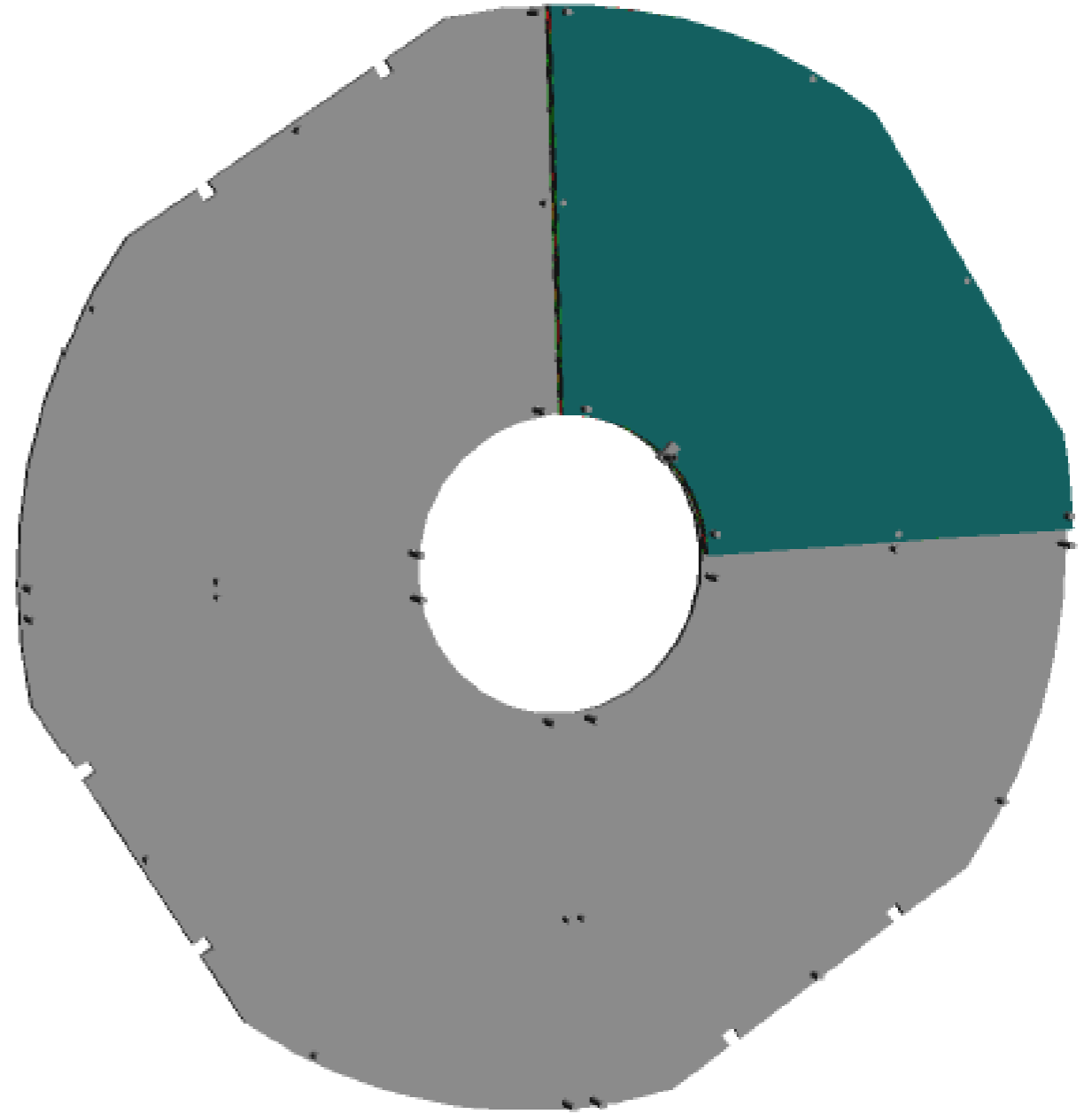
FGT Disk Concept

Nomex disk

- 5 mm thick honeycomb
- alignment pins

FGT quadrant

- single triple GEM detector
- pins preserve shape / tension



FGT Disk Concept

Nomex disk

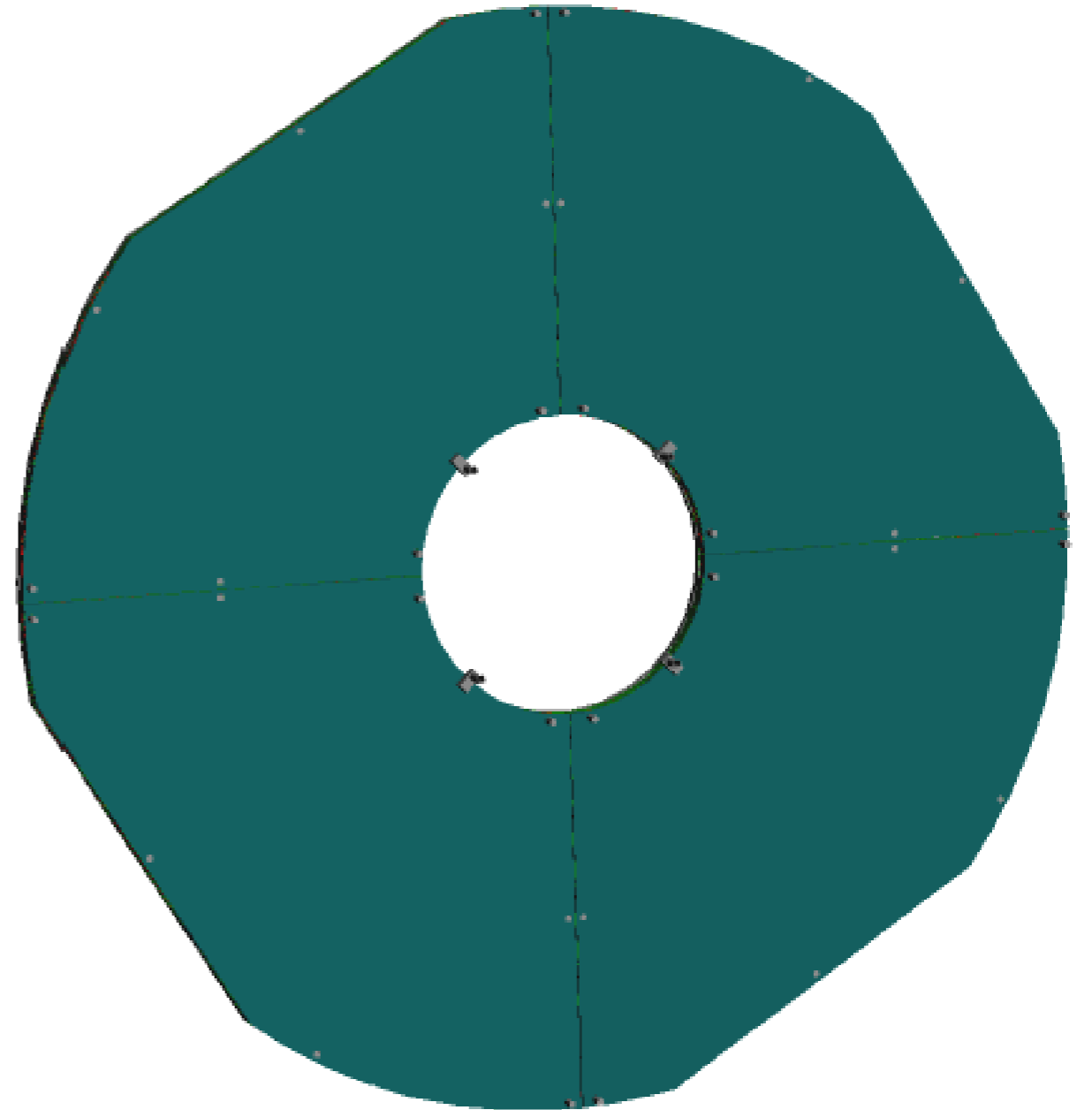
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FGT quadrant

- single triple GEM detector
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4 quadrants per disk

- 1 mm gap between quadrants



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FGT quadrant

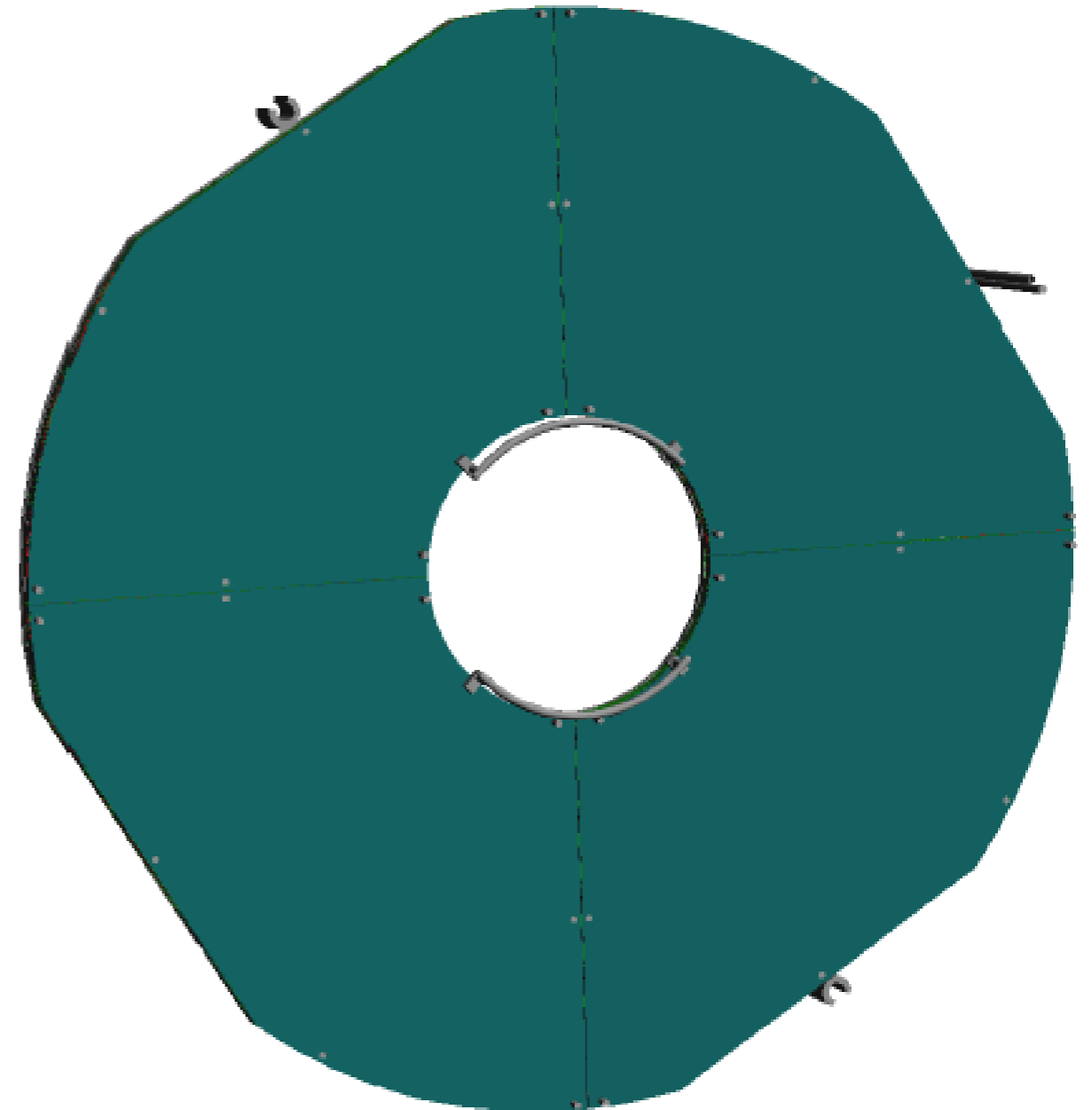
- single triple GEM detector
- pins preserve shape / tension

4 quadrants per disk

- 1 mm gap between quadrants

Infrastructure

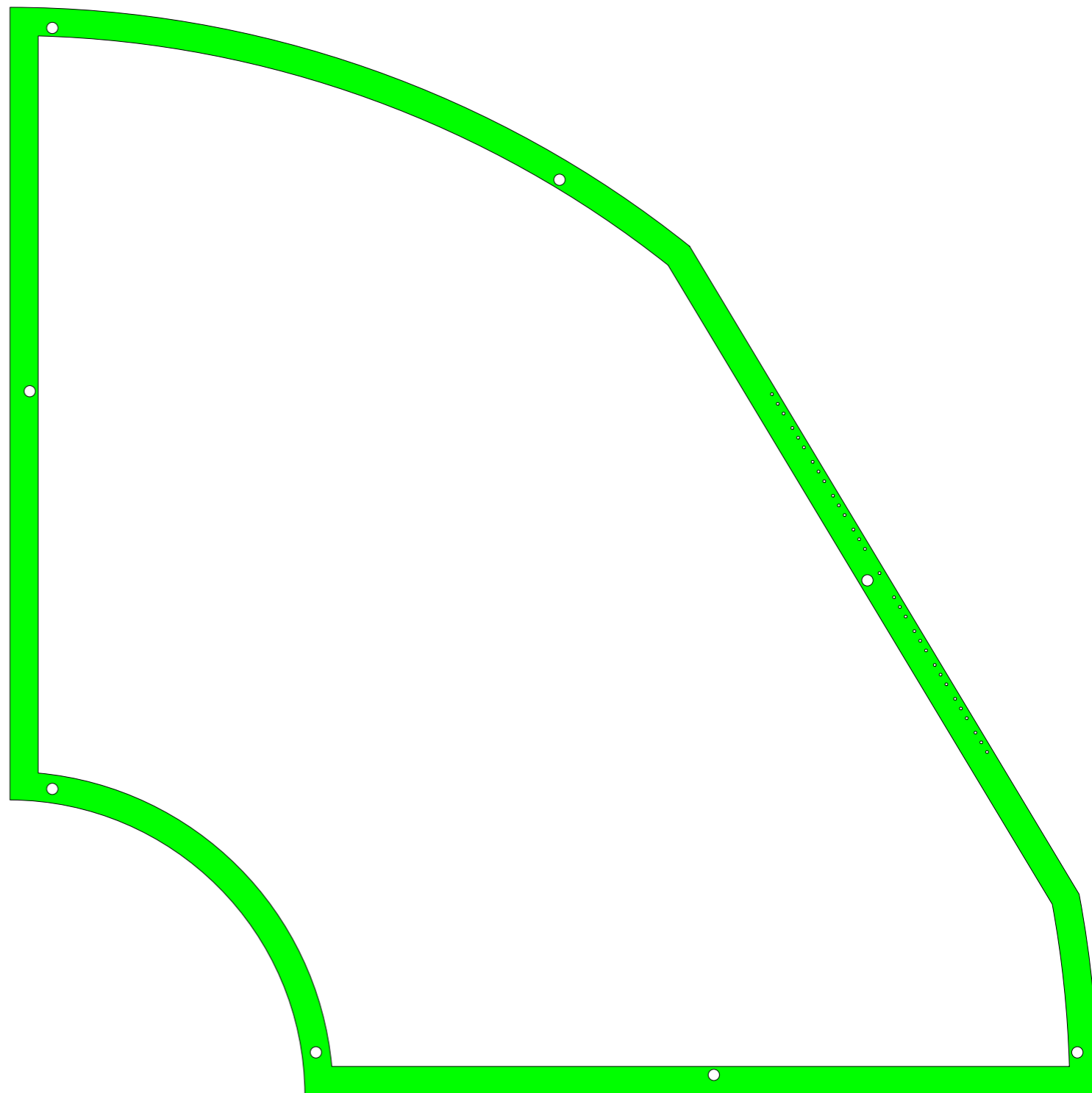
- daisy chain gas supply / return
- rails in WSC position and alignment



FGT GEM Frame

Design

- 1.15 cm wide FR4
- glue trough
- 2 or 3 mm thick
- inner radius 10.35 / 11.5 cm
- outer radius 38.25 / 39.4 cm
- flat at 31°
 - required for TPC structure
 - used for routing services
- 8 holes for alignment pins
 - define position
 - preserve shape and tension
- 32 holes in flat for HV



FGT GEM Foil Design

GEM holes

- 70 micron ID
- 140 micron pitch
- equilateral triangle pattern

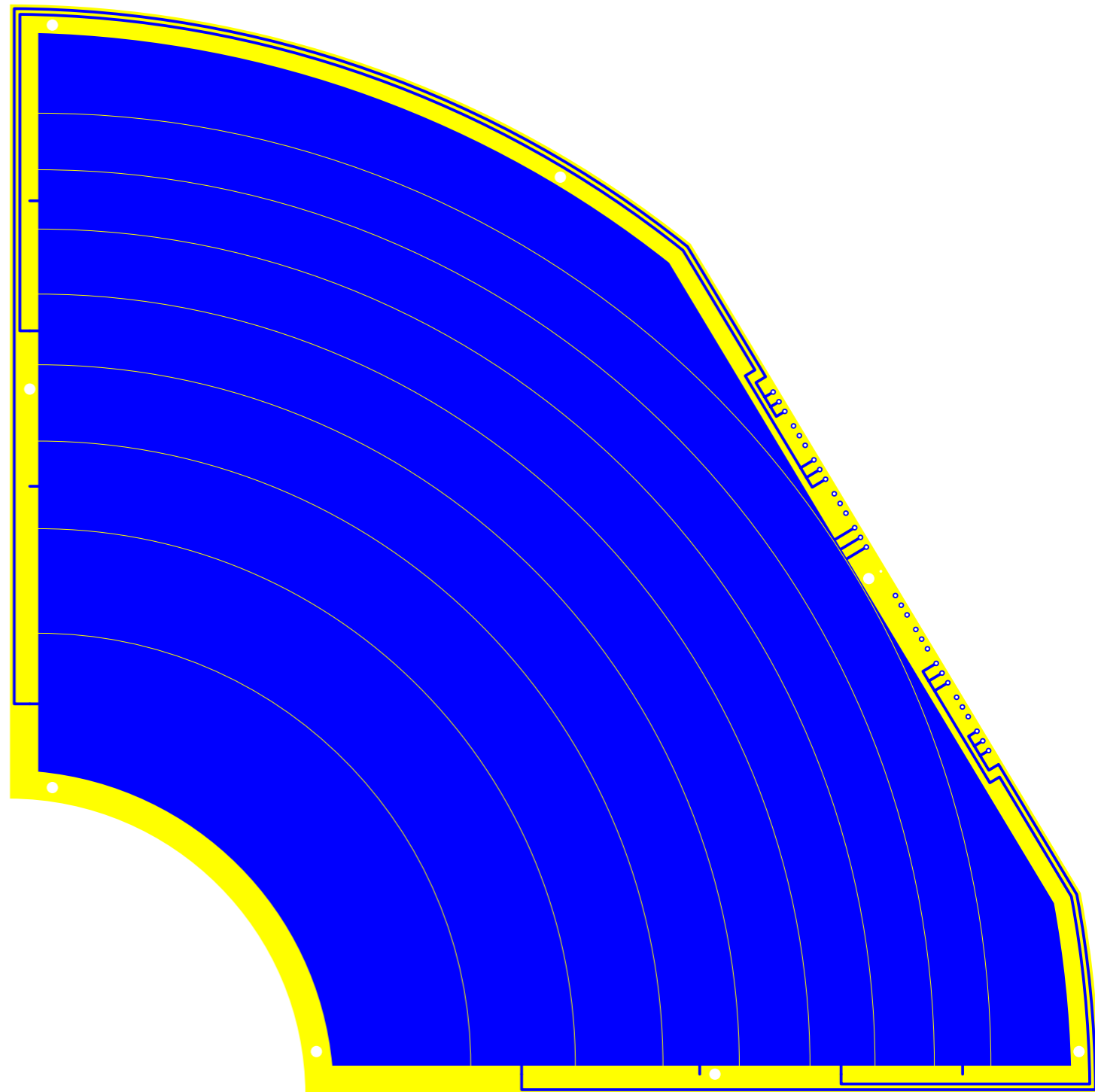
Segmented top side

- 9 segments
- ~100 cm²
- reduce breakdown damage
- 200 gap between segments

Bottom side not segmented

Routing for HV

Produced by Tech-Etch



Tech-Etch, Plymouth, MA

Photo-etching and flexible circuit board manufacturer

SBIR for GEM foils

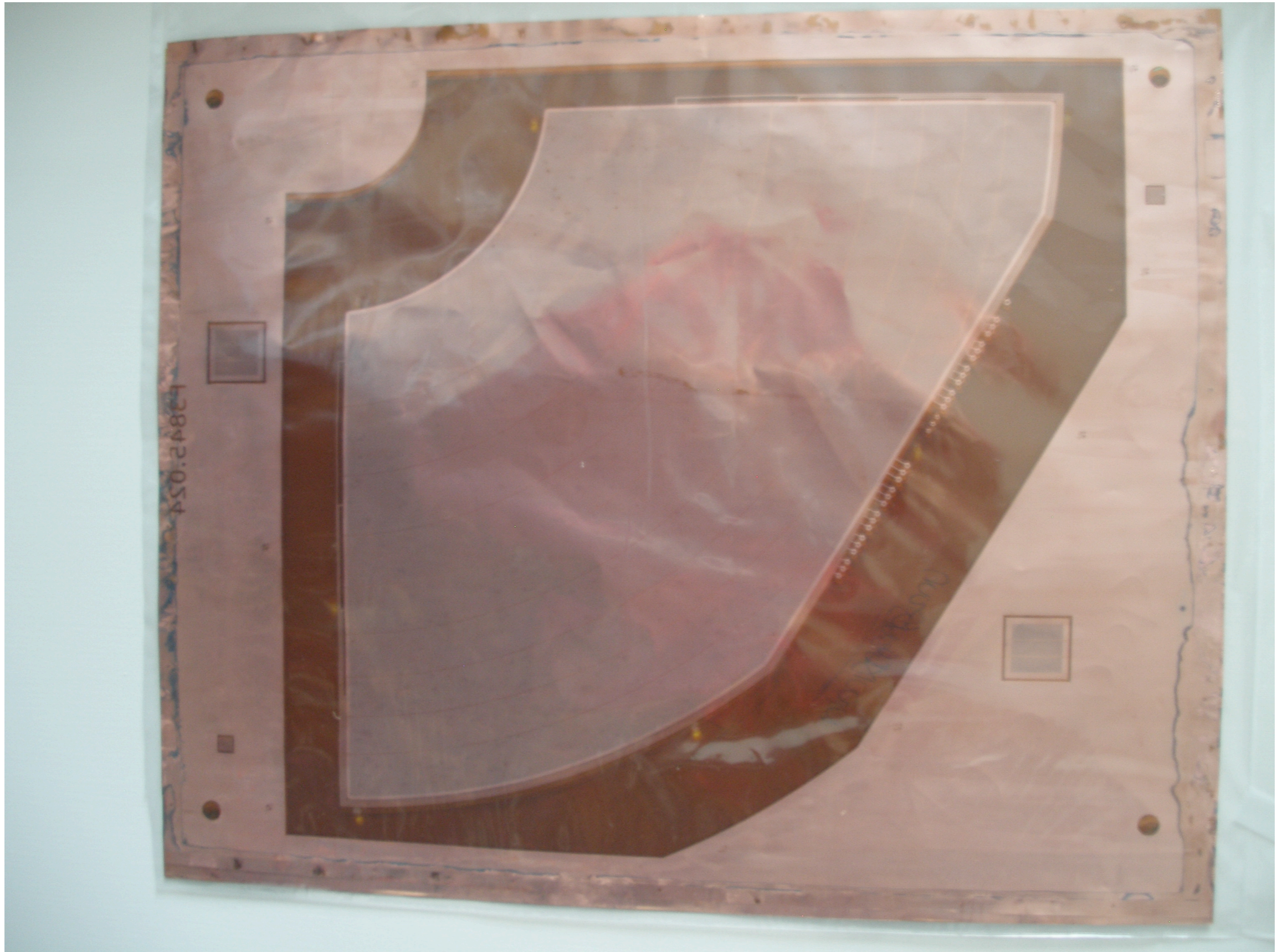
- dedicated line for GEM foils
- measurement and QA

New SBIR for 2D readout

- using chemical etching



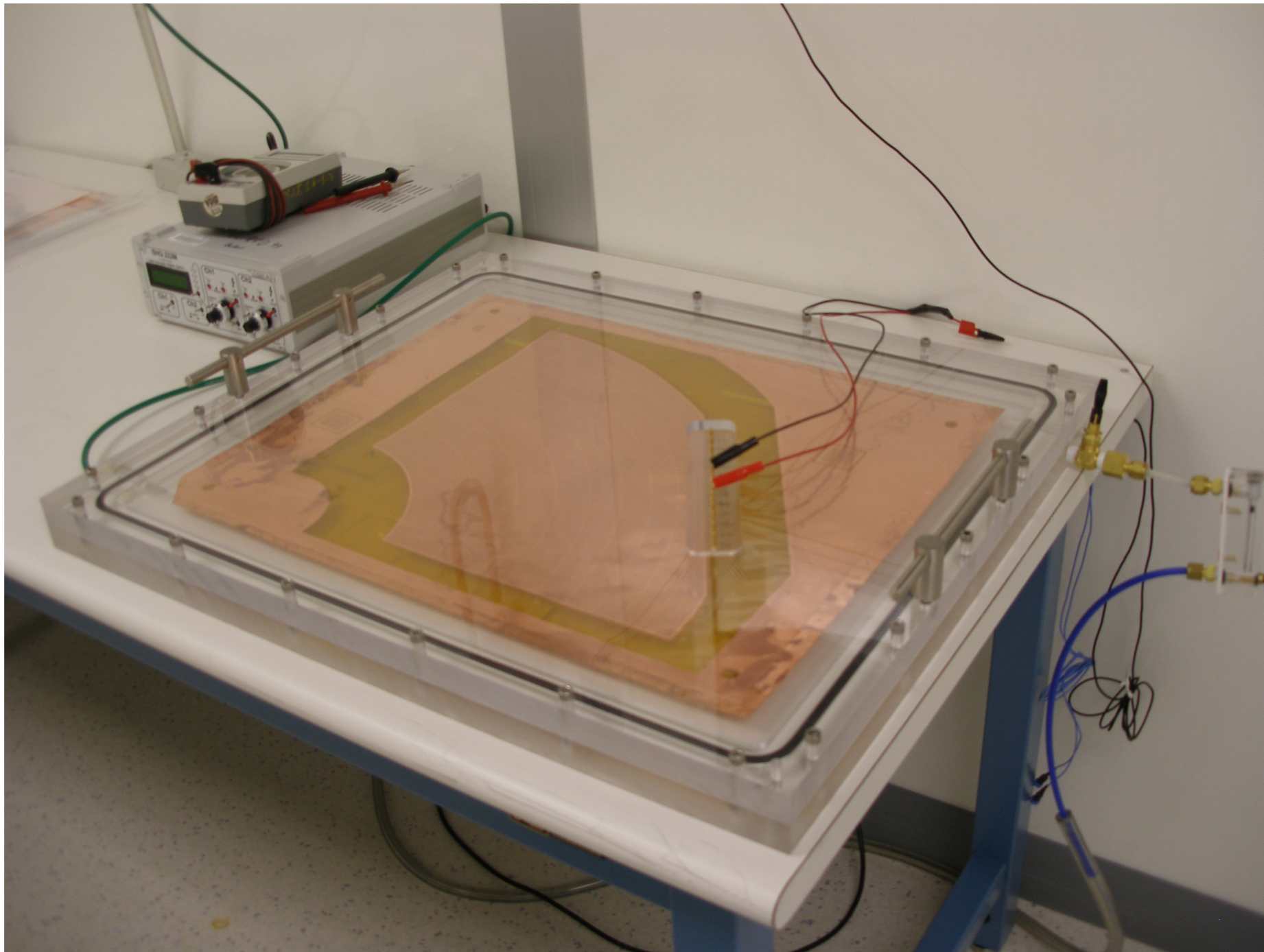
Tech-Etch FGT GEM Foil



HV Testing of GEM Foils - R. Corliss (MIT)

Minimal volume chamber

- rapid flush with dry N₂
- 5 l / min
- test to 700 V in 100 V steps
- measure current to 0.1 nA



HV Tests

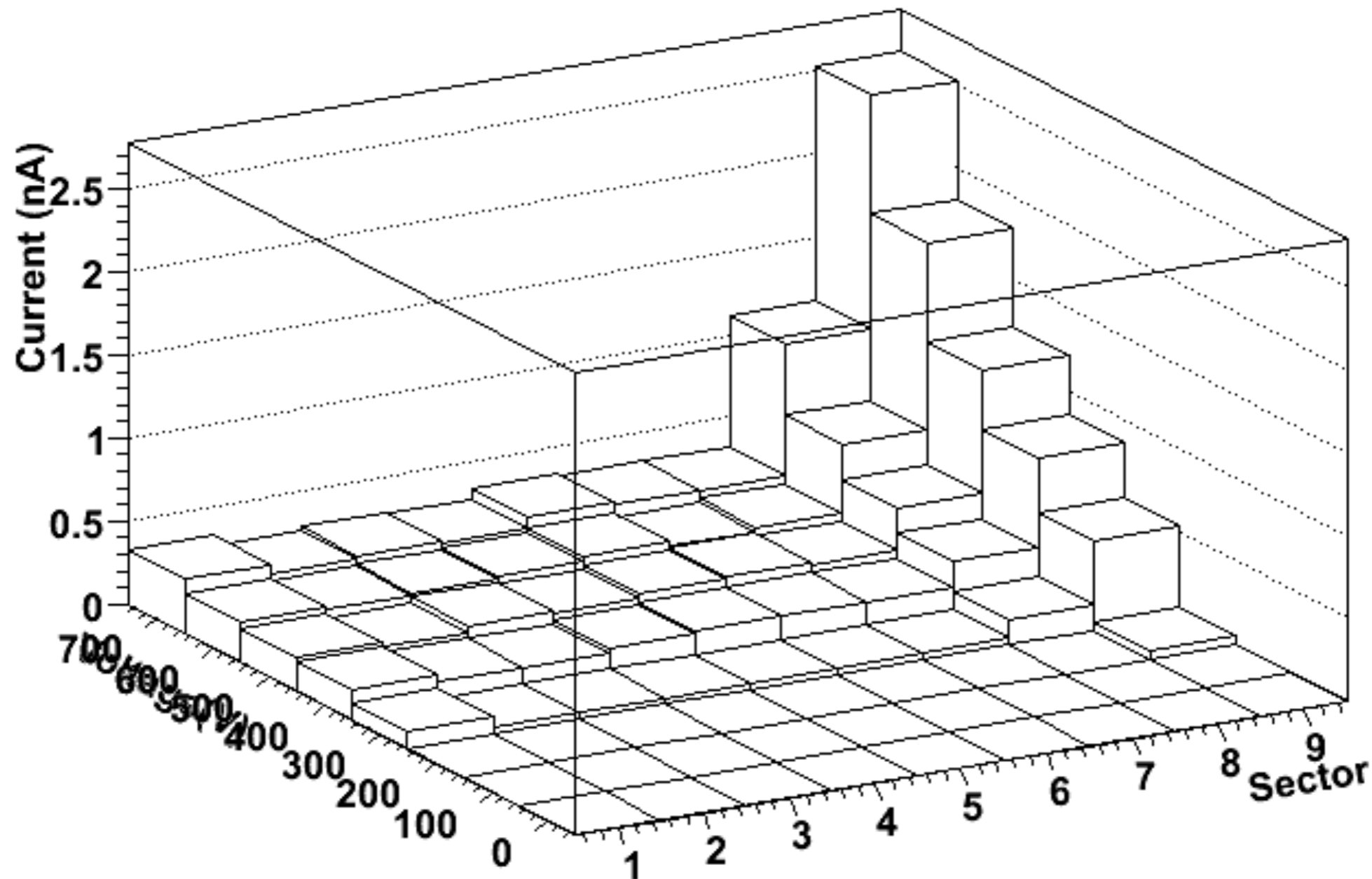
Tech-Etch - average 8 foils

- test to 700 V

- systematically higher currents in segments 8 and 9
- cleaning ? (R. de Oliveira)

Dark Currents in average GEM foil

foilA

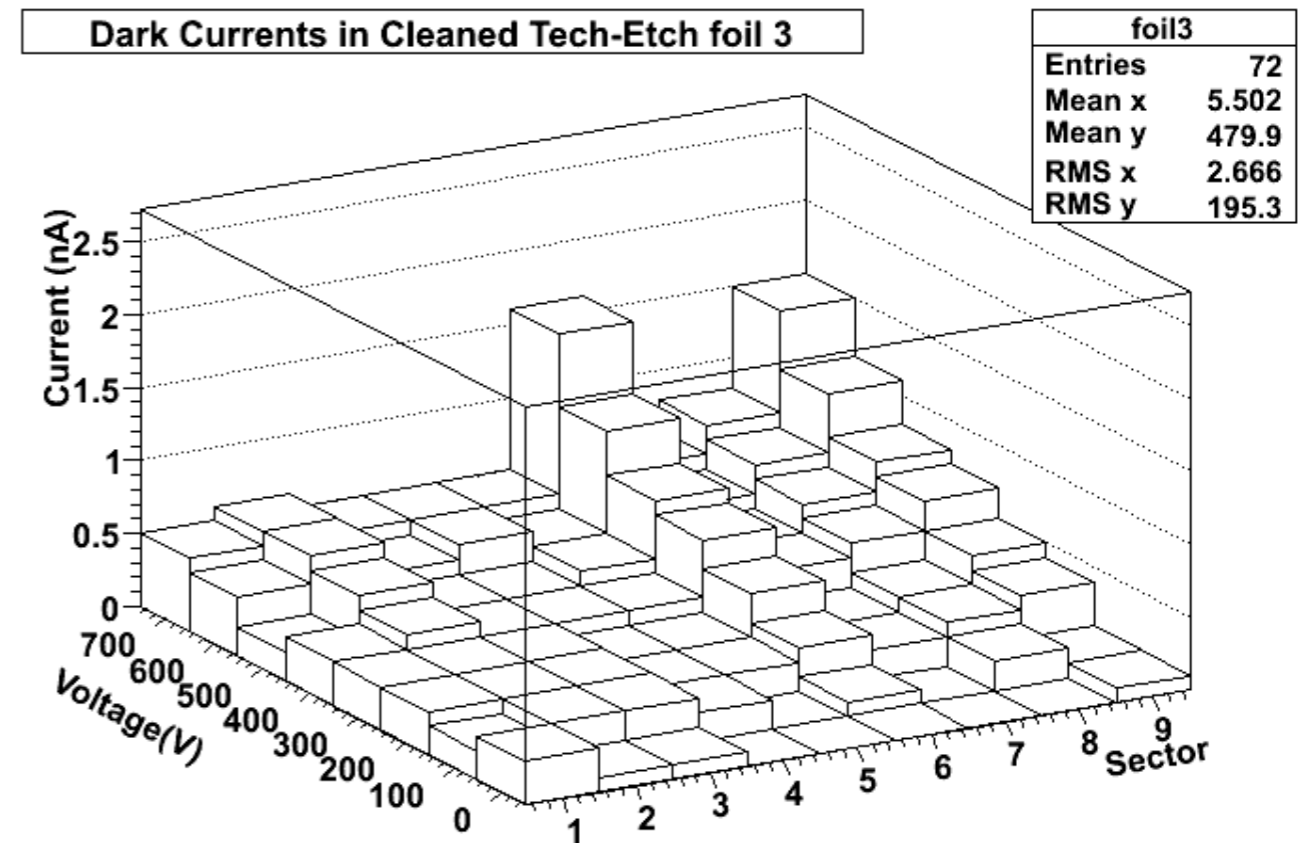
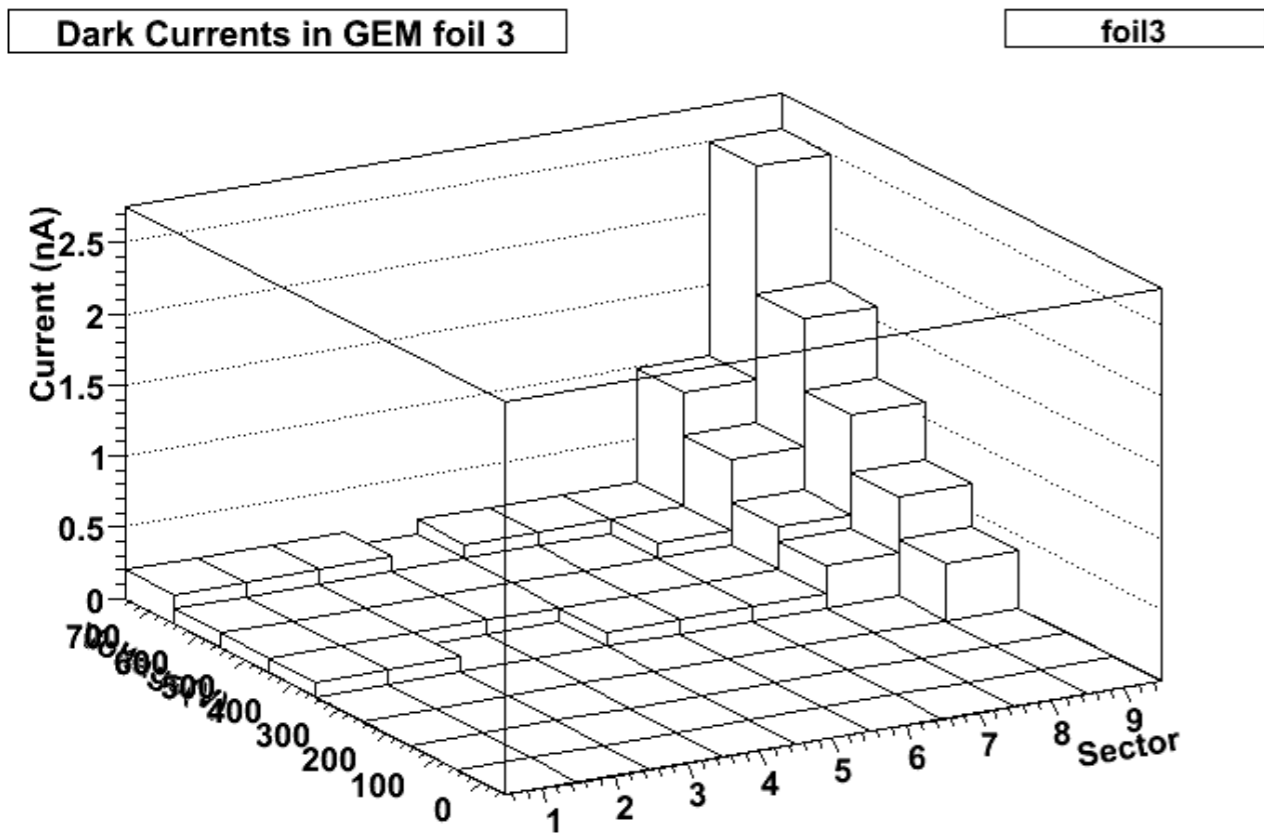


HV Tests

Before re-cleaning

After re-cleaning

- improved ?



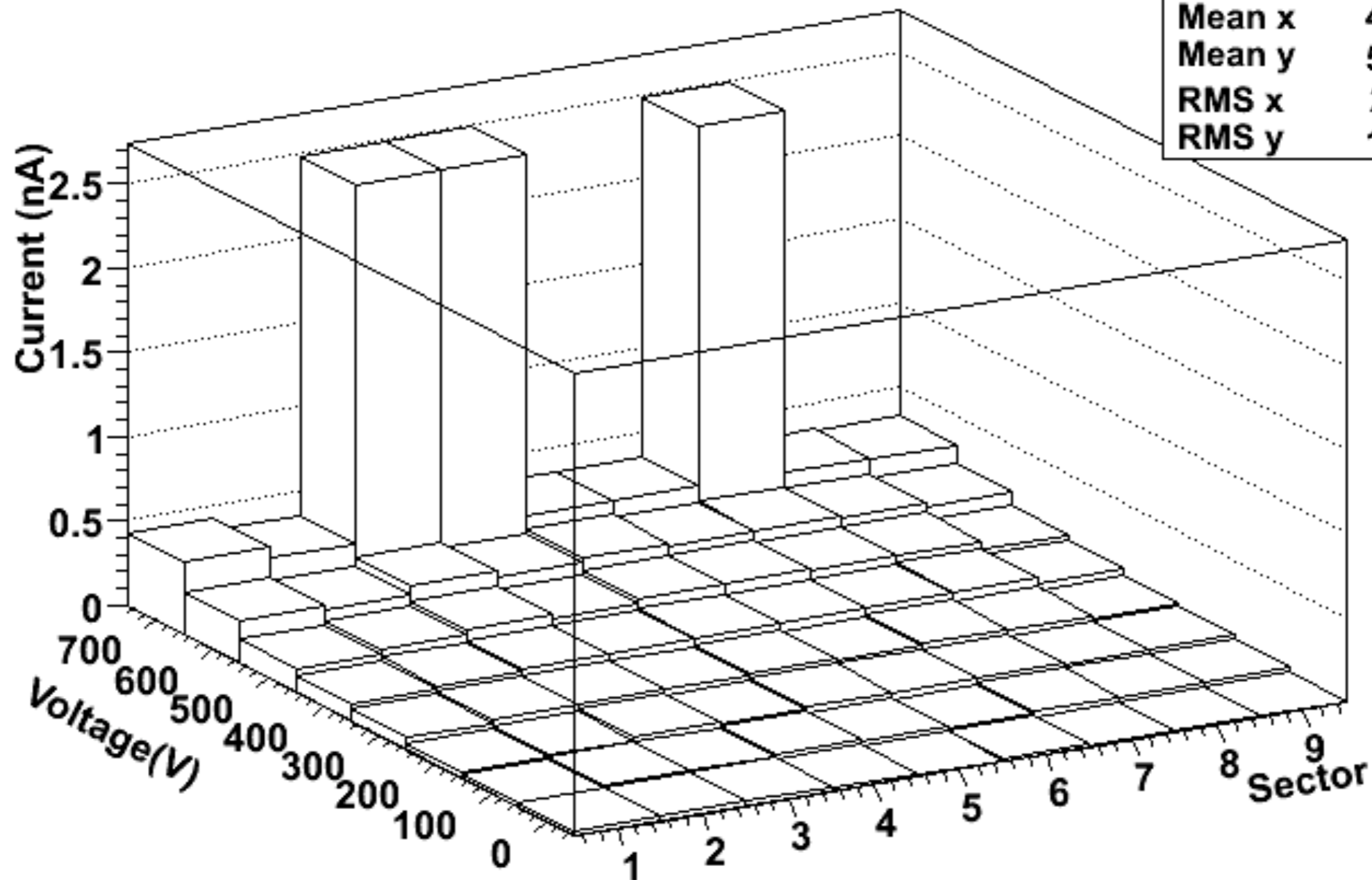
HV Tests

CERN - GEM foil 2

- we test to 700 V
- CERN tests to 600 V

- higher currents at 700 V
- often unstable above 600 V
- otherwise quieter

Dark Currents in CERN foil 2



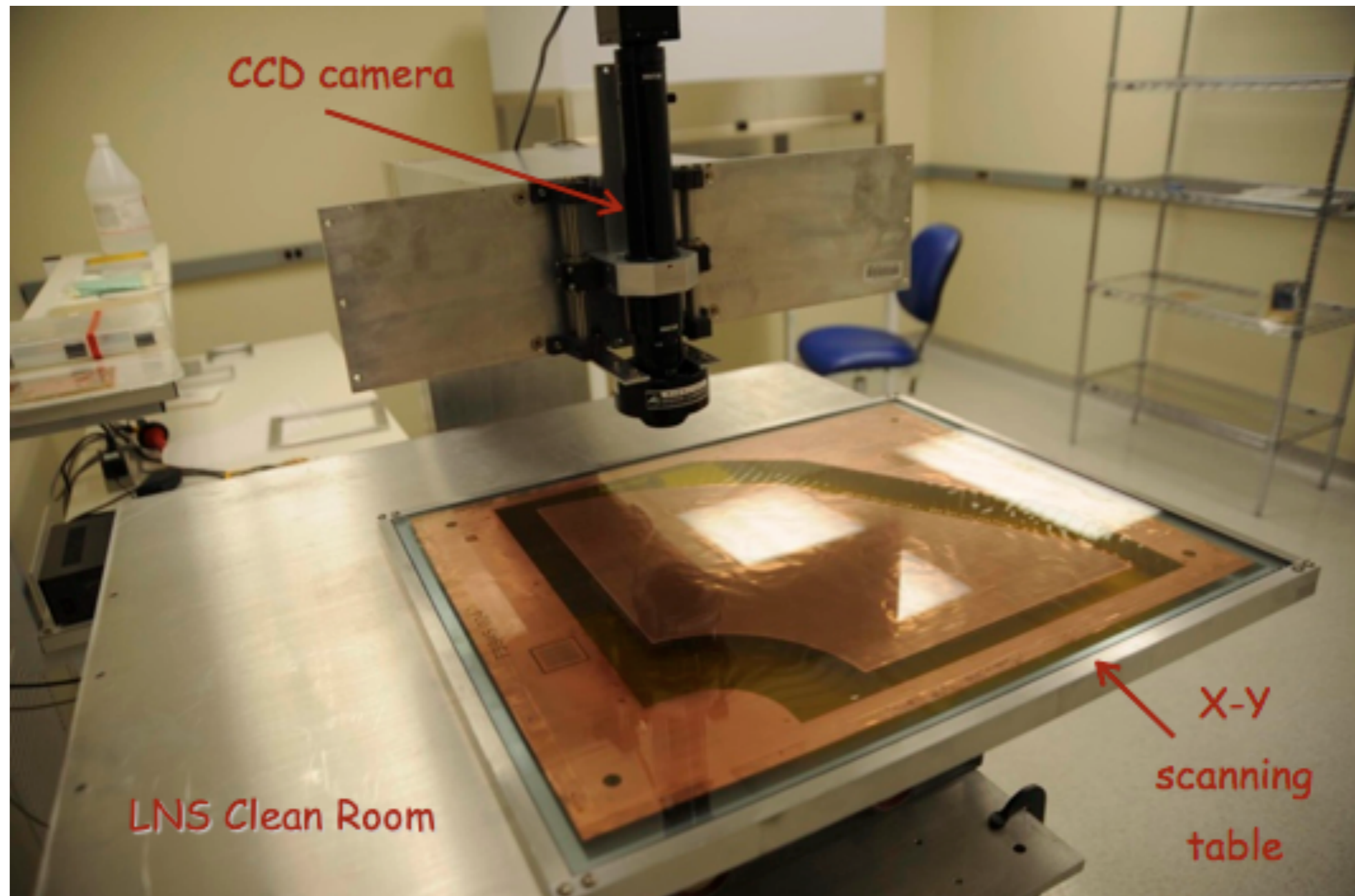
CCD GEM Foil Scans - J. Seele, W. Leight (MIT)

Small X/Y table

- scan FGT foils in 6 sections
- measure from both sides

Measure hole diameters

- light above - outer diameter
- light below - inner diameter



CCD GEM Foil Scan - Inner Hole Diameter

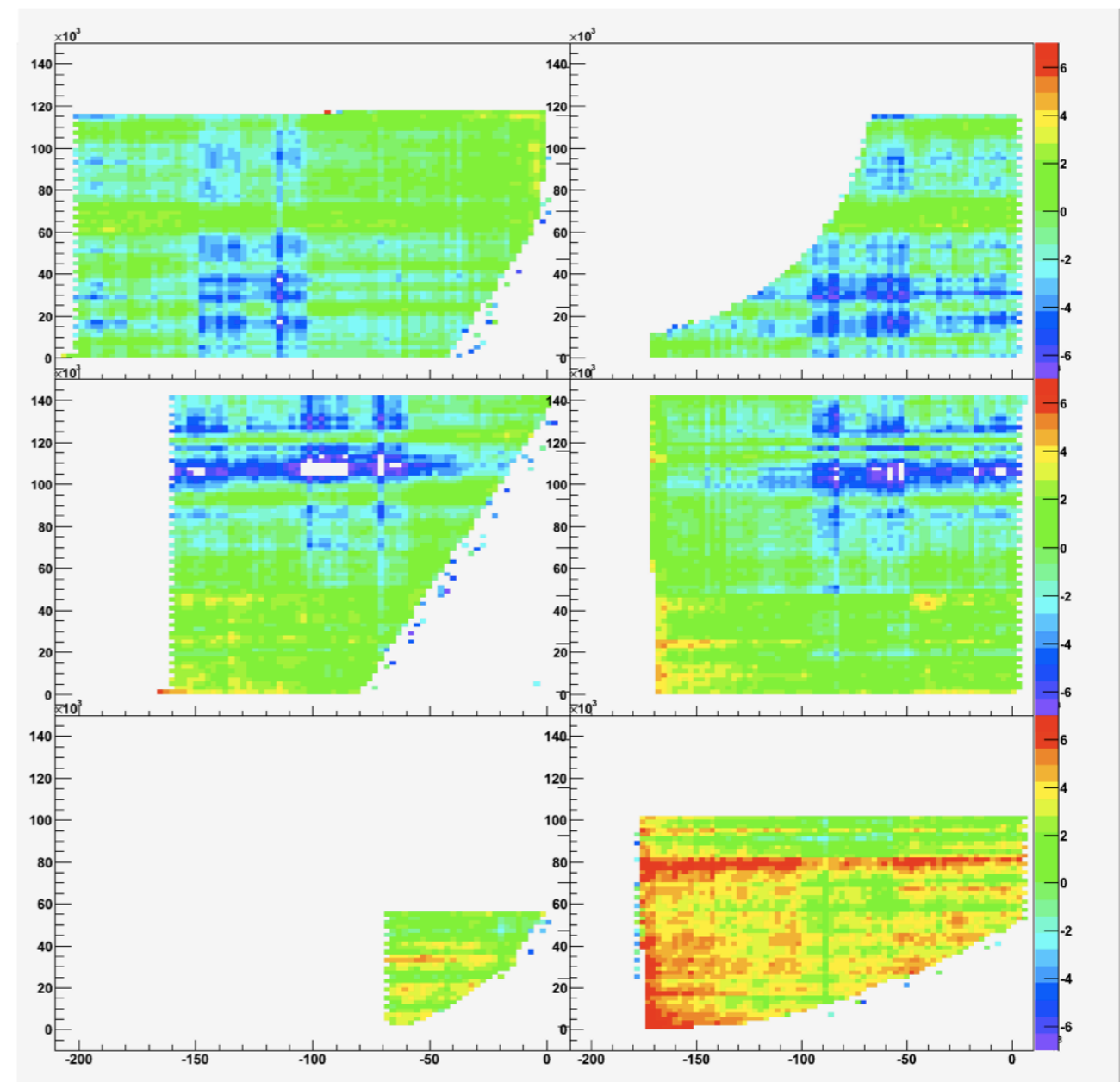
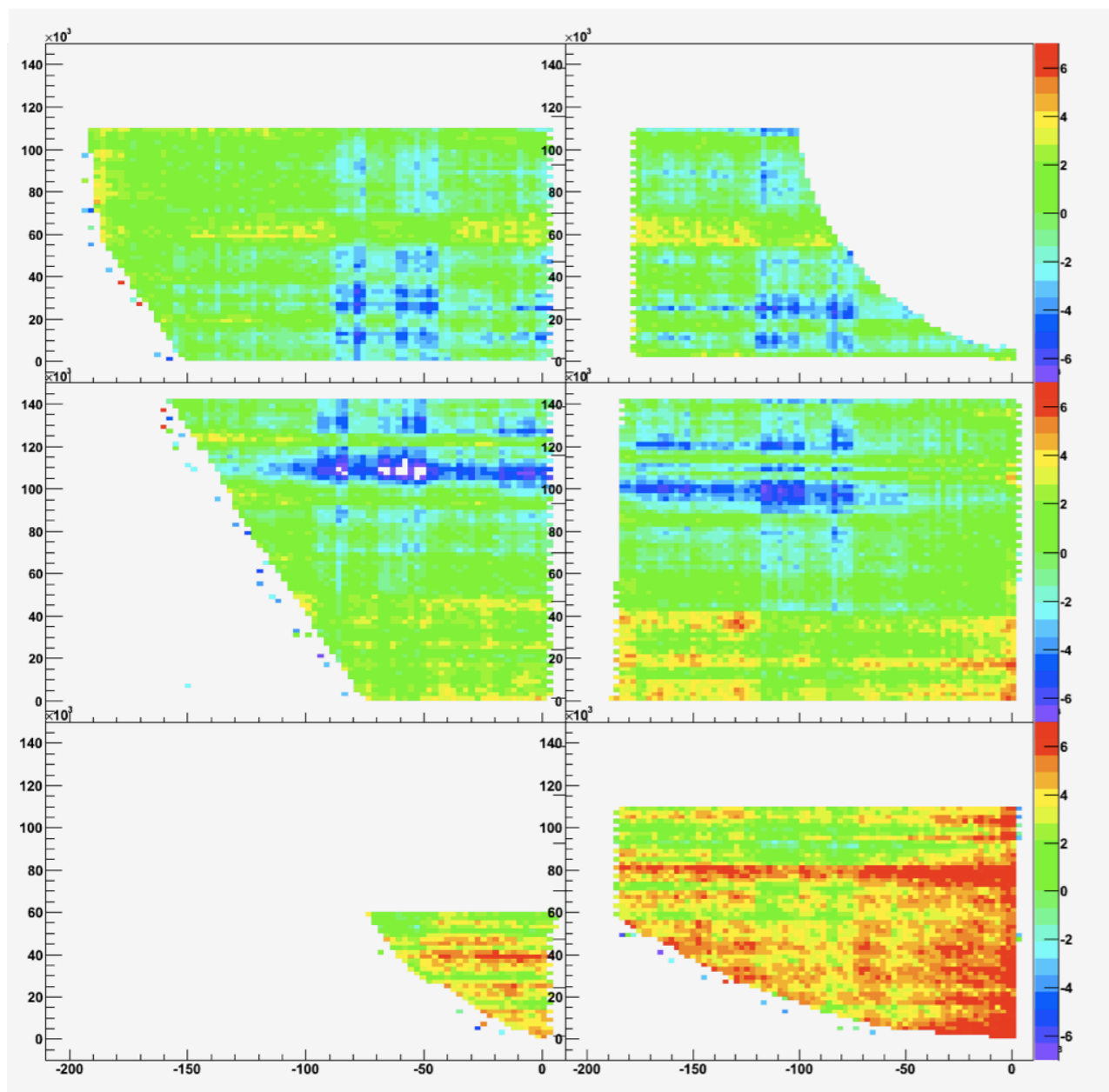
Tech-Etch - GEM foil 2

Inner hole diameter

- blue 6 micron below average
- red 6 micron above average

Striped pattern understood

- laser direct imaging
- fix (hopefully) with glass masks



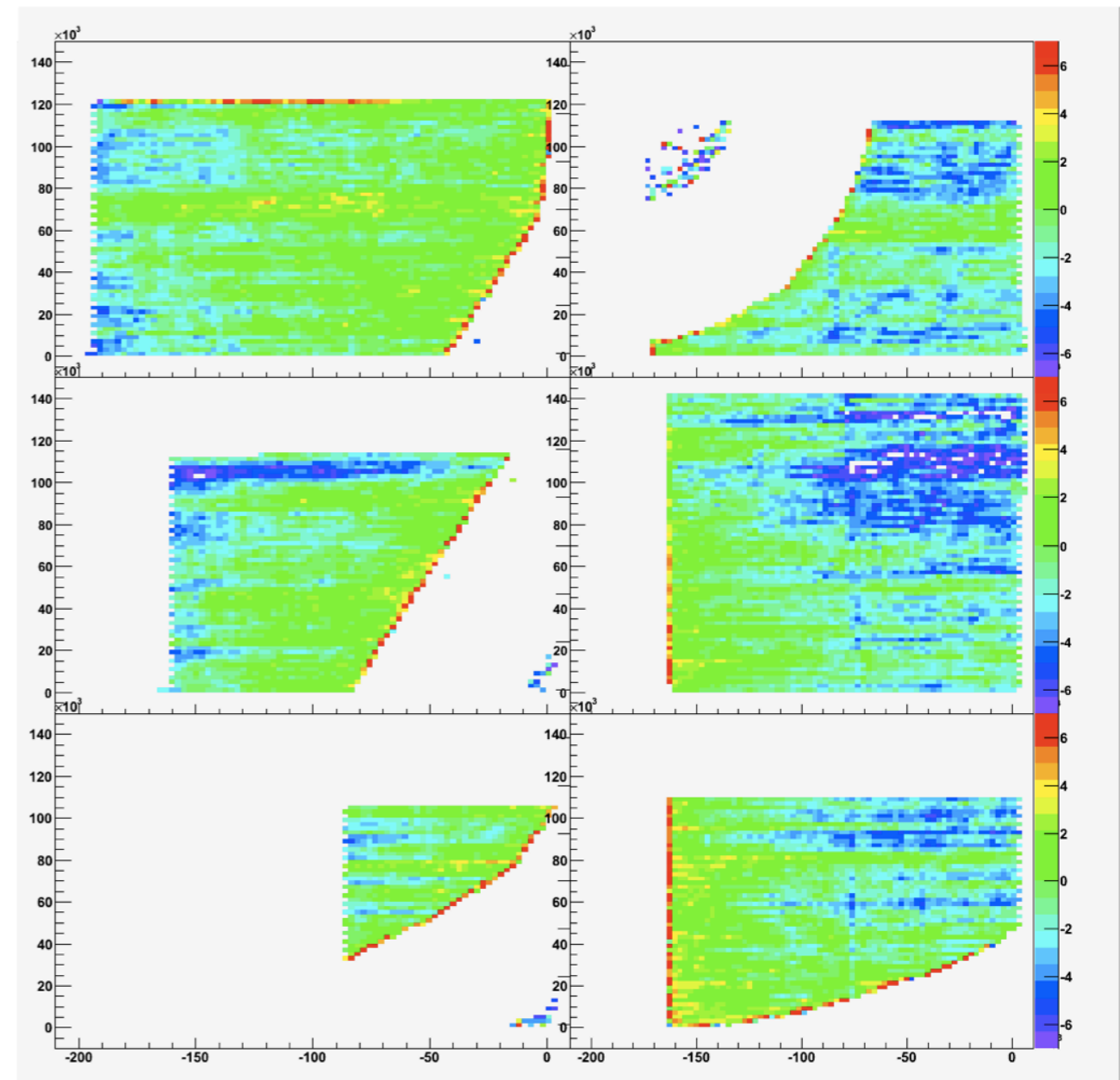
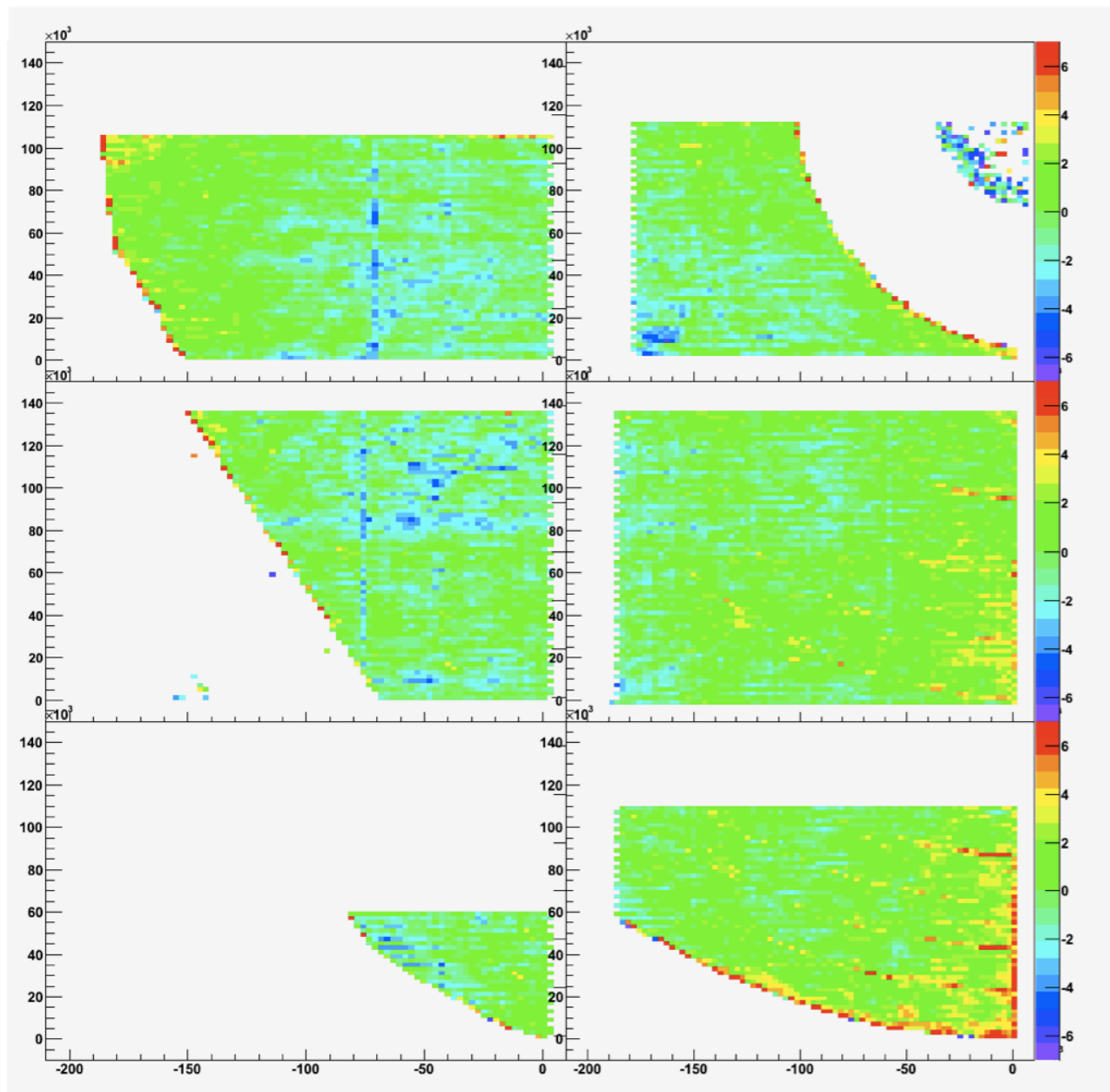
CCD GEM Foil Scan - Outer Hole Diameter

Tech-Etch - GEM foil 2

- similar striped pattern

Outer hole diameter

- blue 6 micron below average
- red 6 micron above average



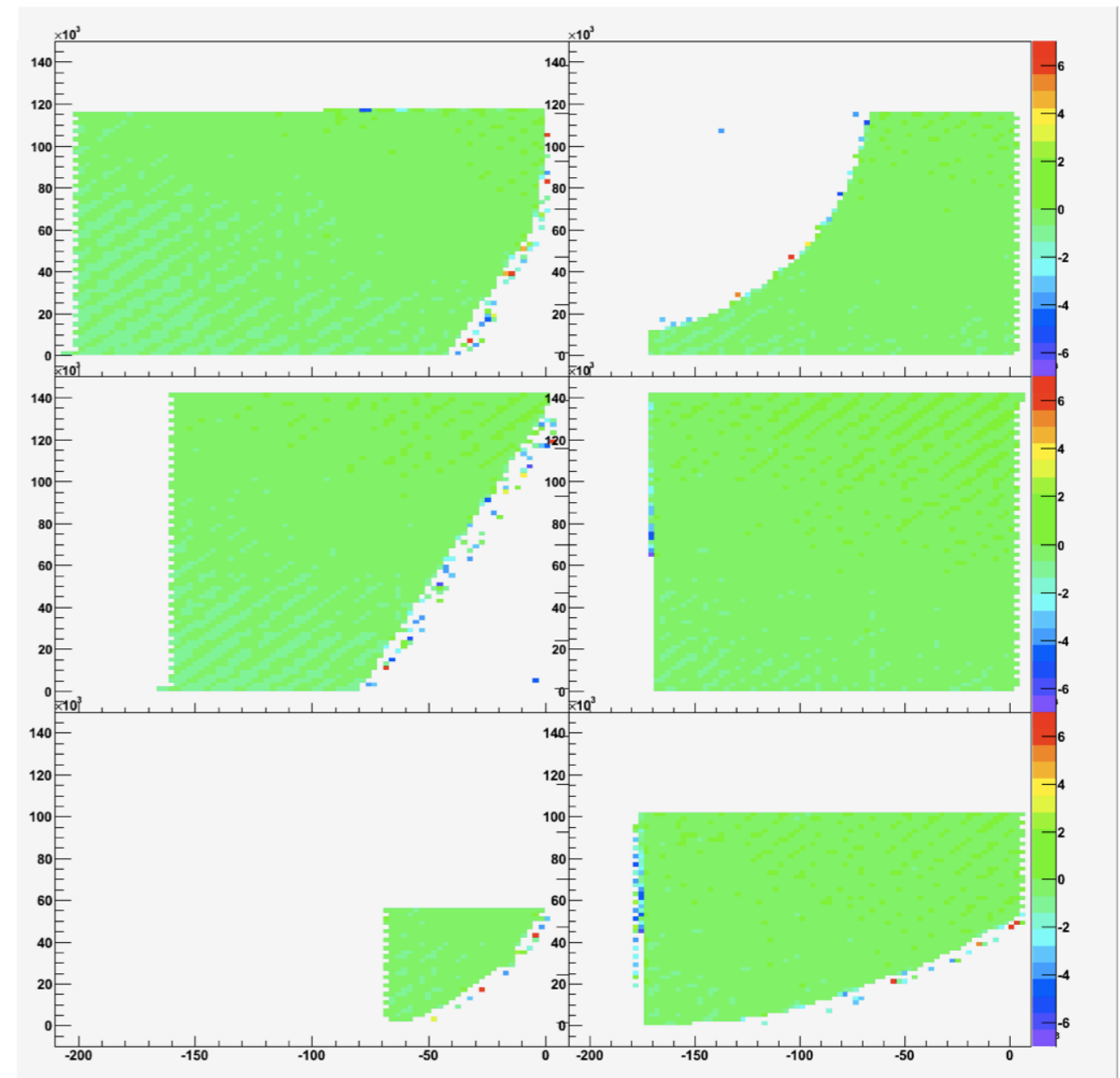
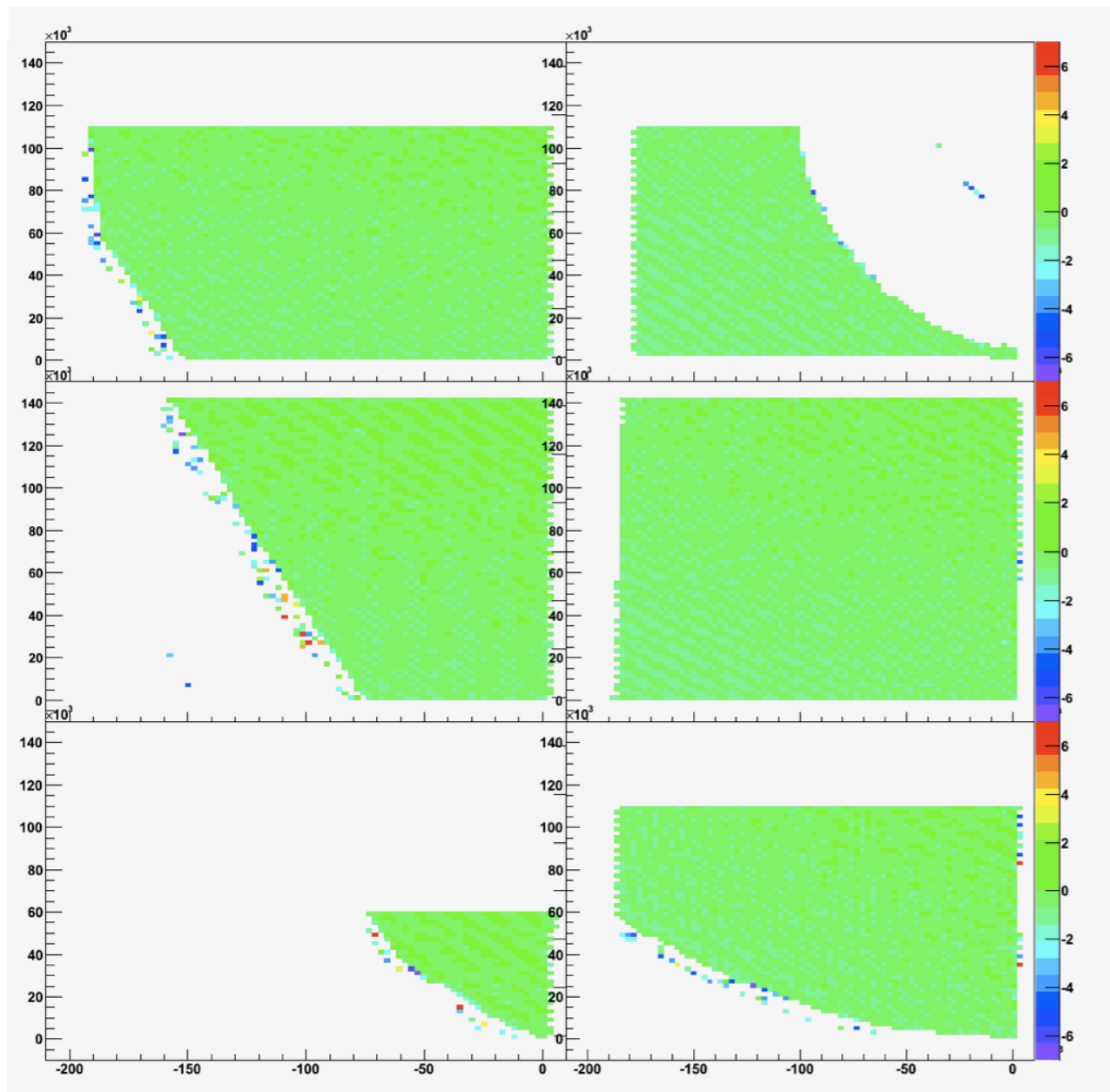
CCD GEM Foil Scan - Hole Pitch

Tech-Etch - GEM foil 2

- hole pitch very uniform

Hole pitch

- blue 6 micron below average
- red 6 micron above average

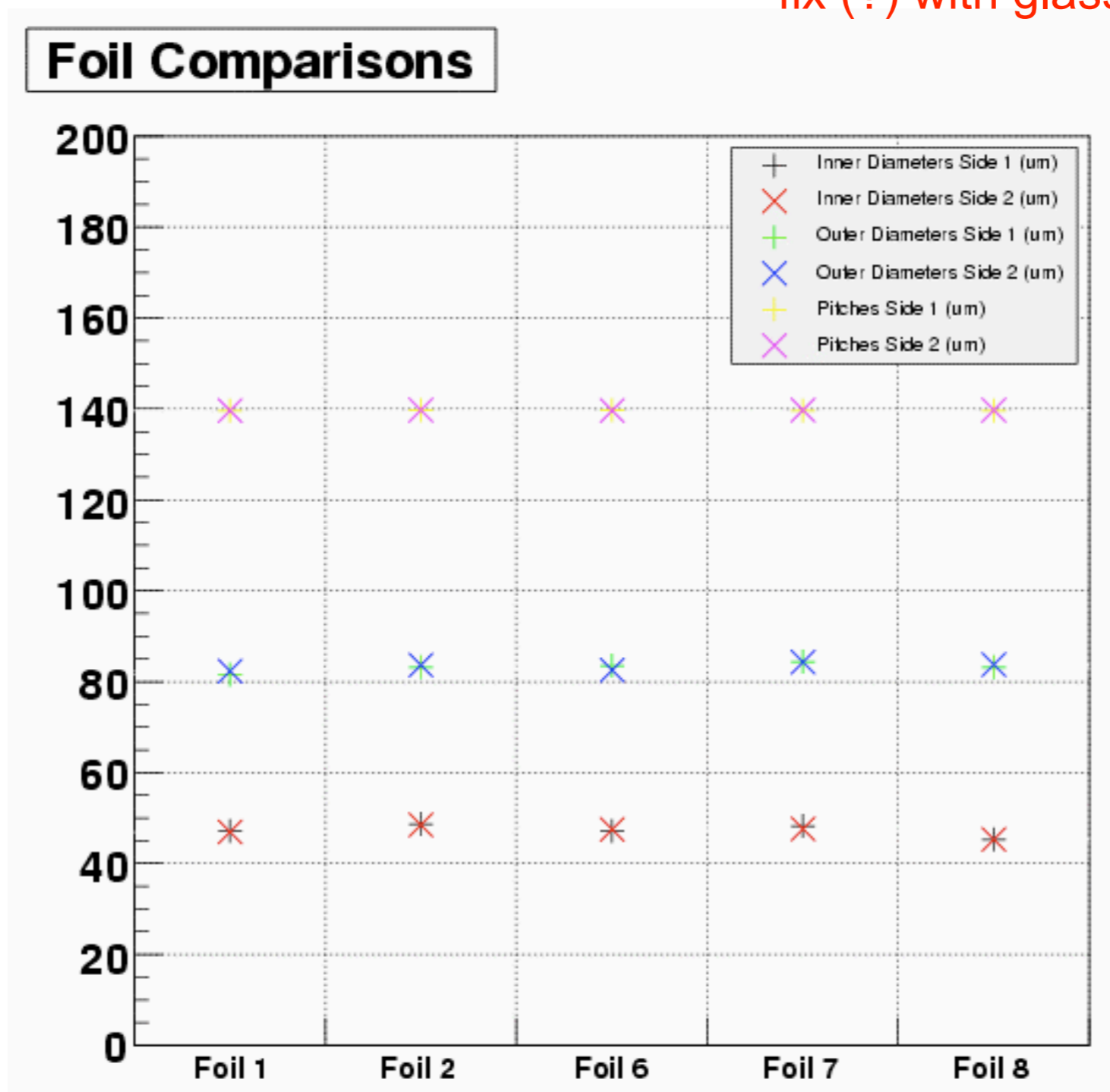


CCD GEM Foil Scans

Tech-Etch foils

- consistency in production good
- diameters slightly off 70 / 50

- holes also offset from one side to the other
 - LDI
 - fix (?) with glass masks



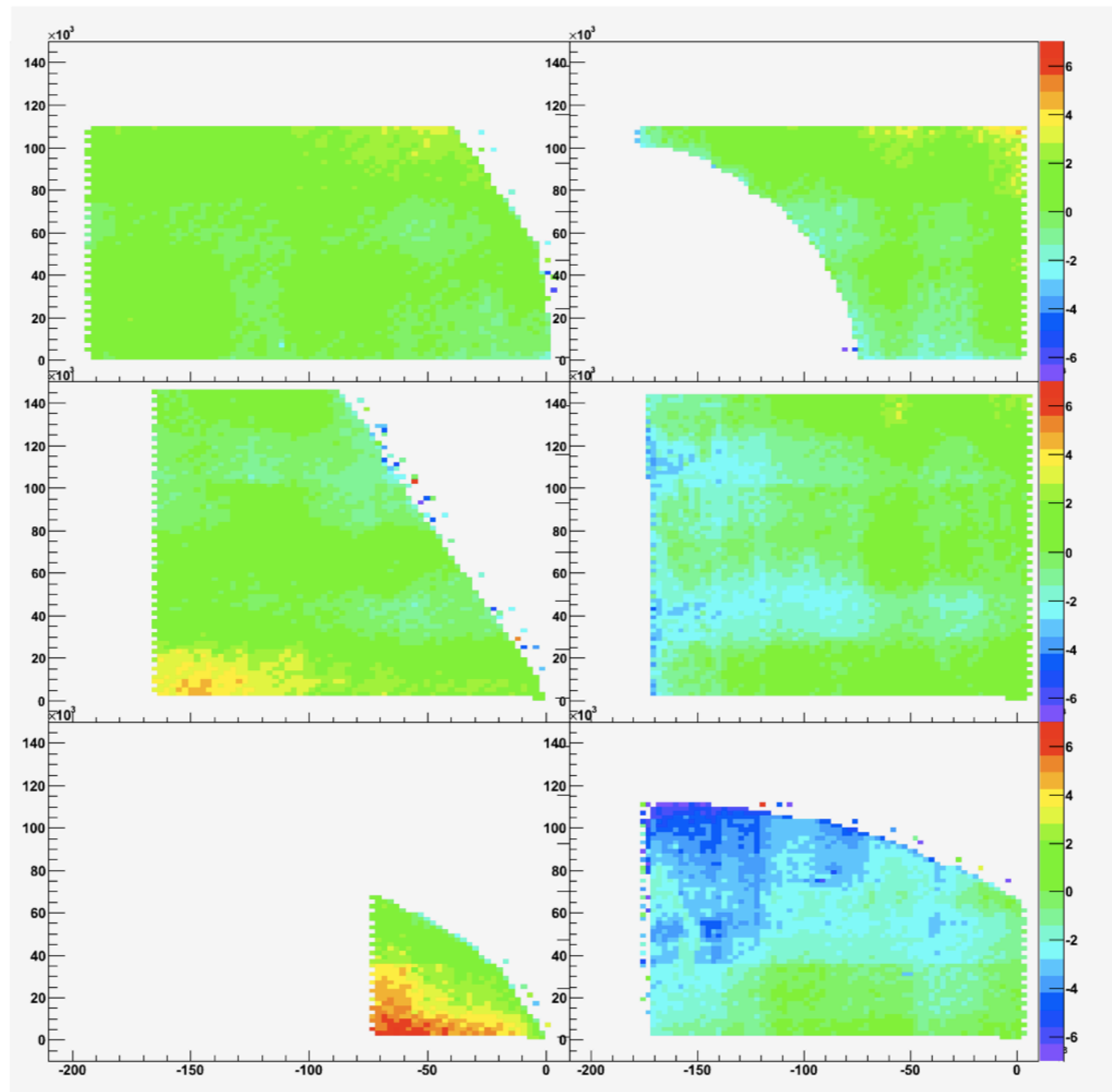
CCD GEM Foil Scan - Inner Hole Diameter

CERN - GEM foil 2

- stripe pattern not so obvious
- inner hole diameter more uniform (?)

Inner hole diameter

- blue 6 micron below average
- red 6 micron above average



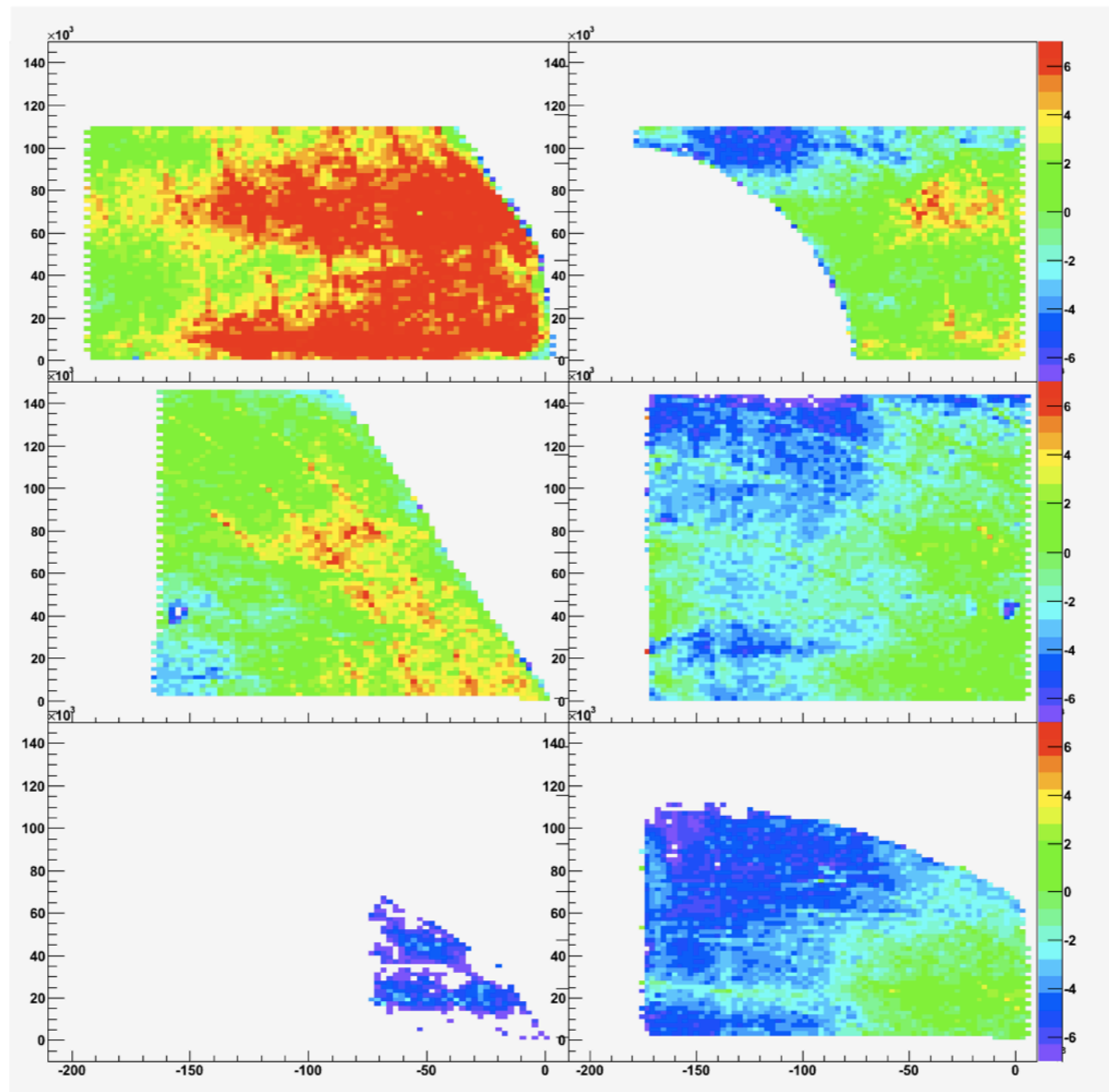
CCD GEM Foil Scan - Outer Hole Diameter

CERN - GEM foil 2

- stripe pattern not so obvious
- outer diameter not so uniform
 - distinct regions with different diameters

Outer hole diameter

- blue 6 micron below average
- red 6 micron above average



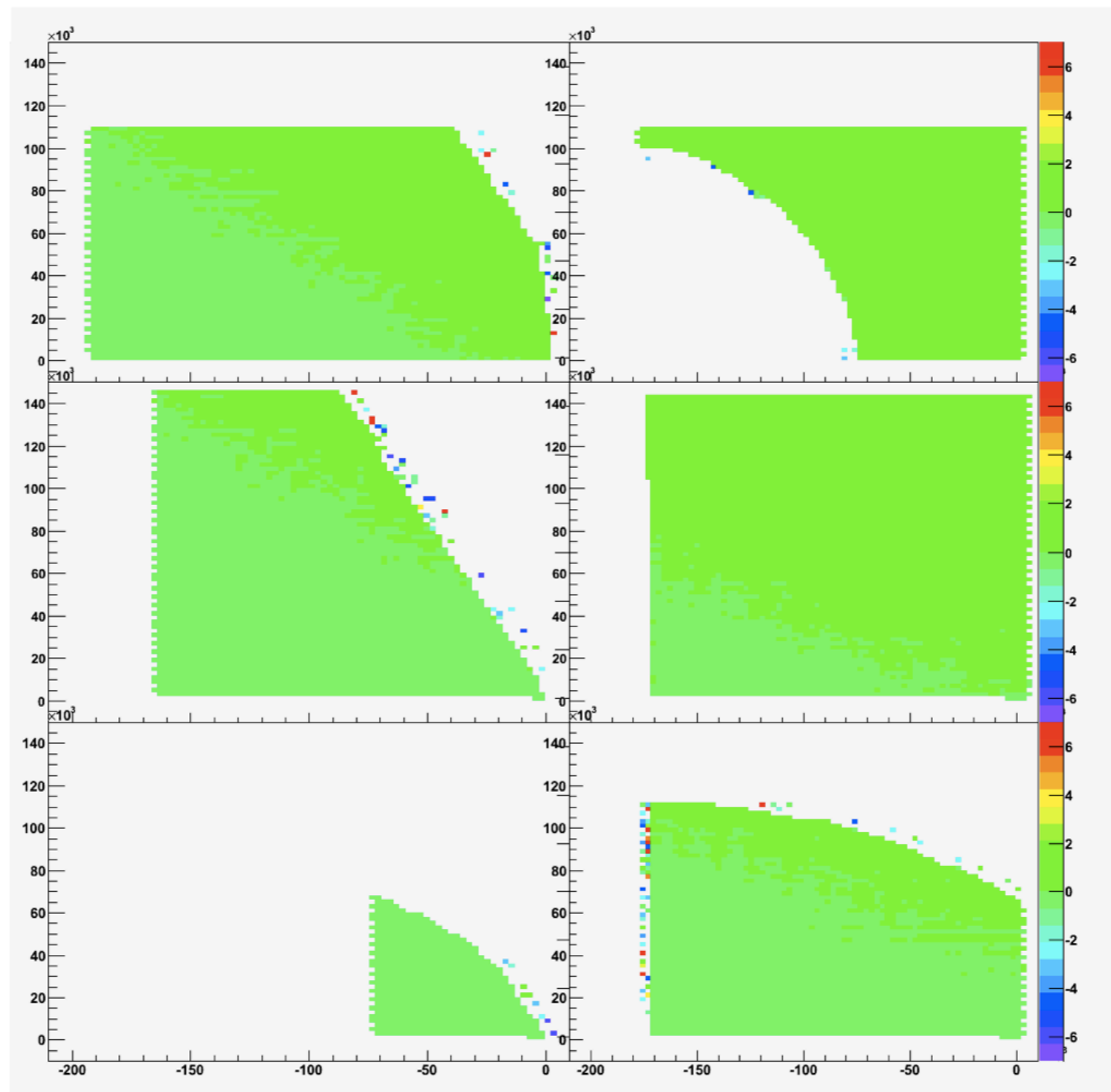
CCD GEM Foil Scan - Hole Pitch

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Hole pitch

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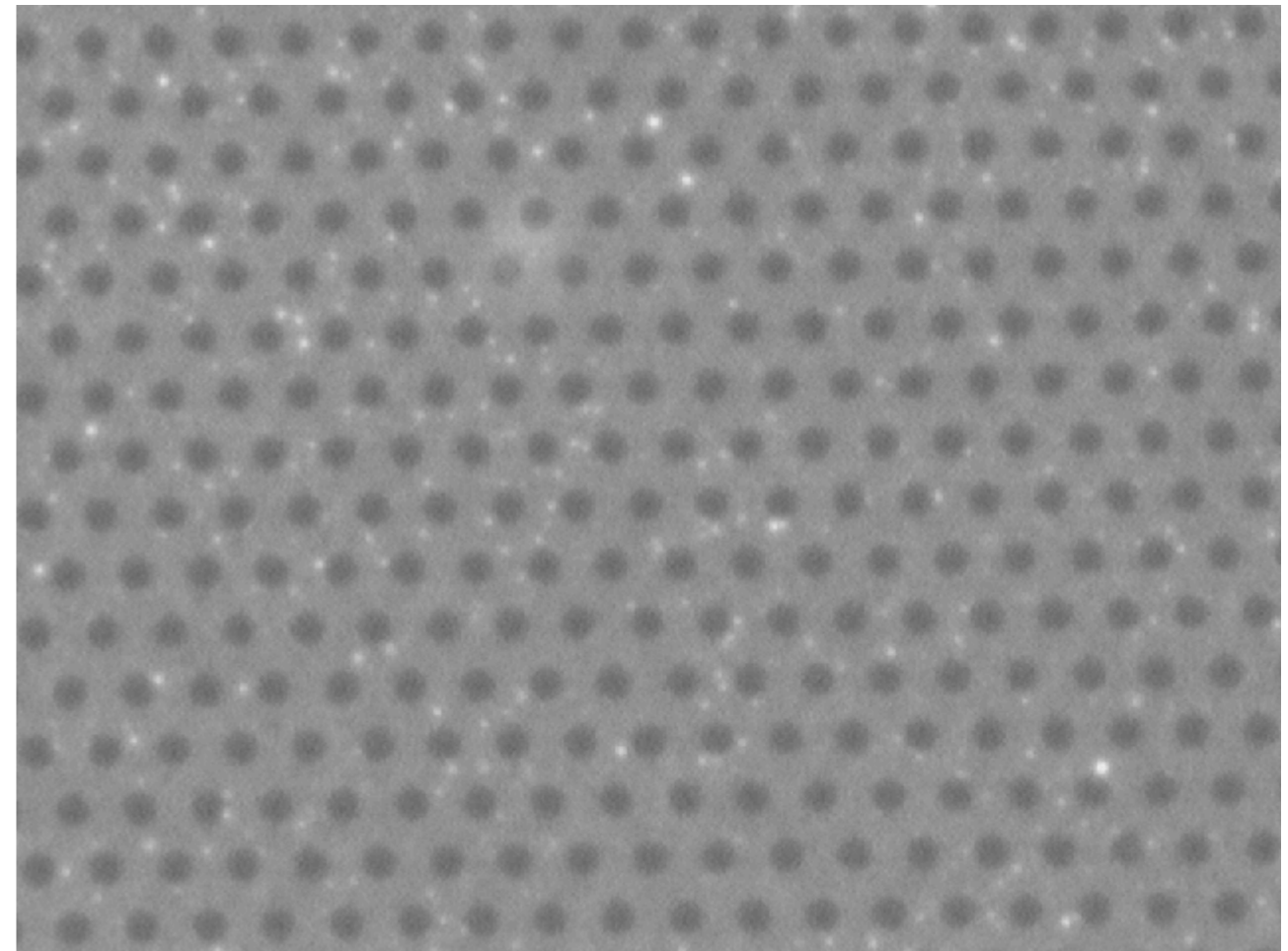
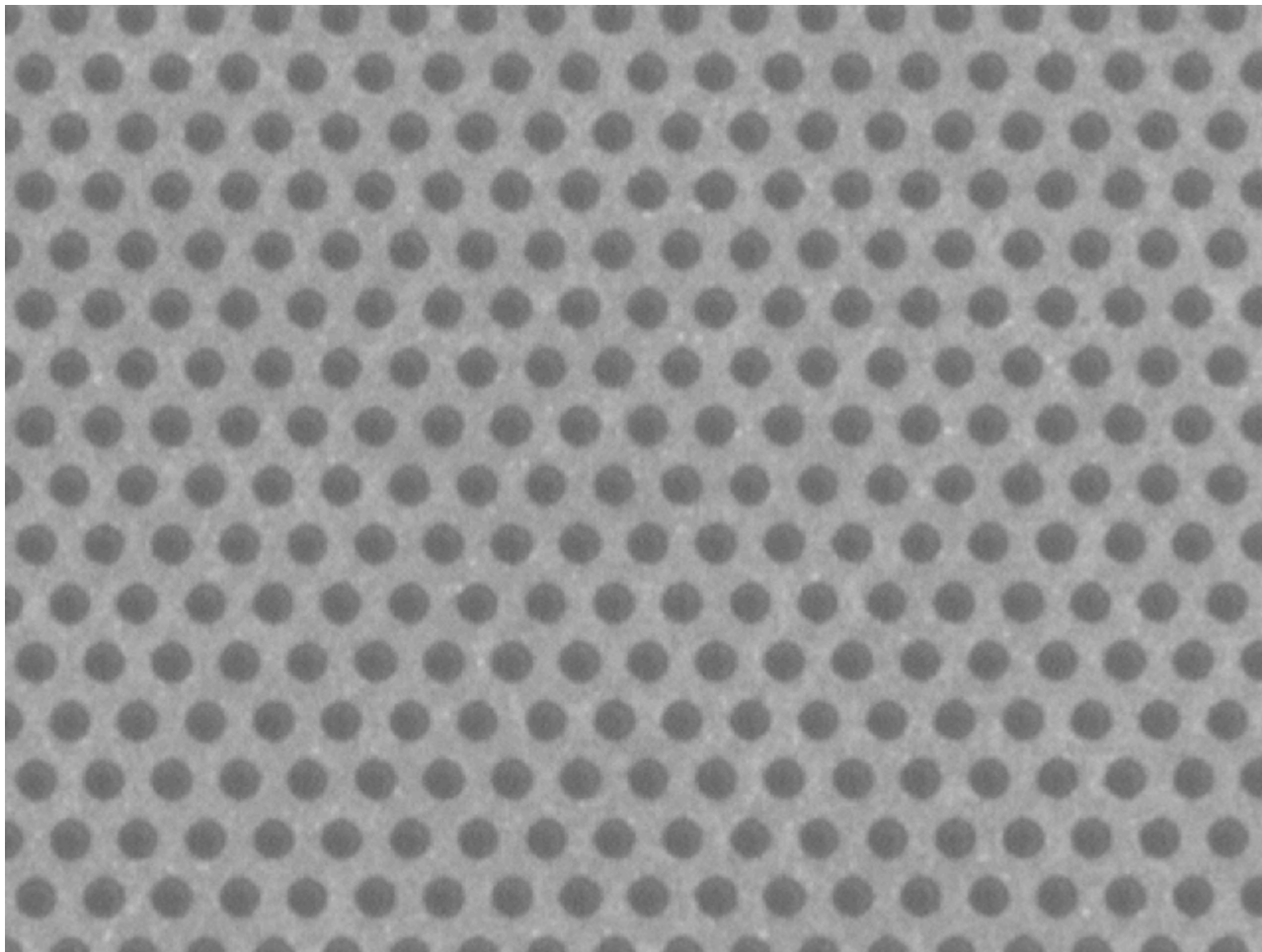
CCD GEM Foil Scan

Tech-Etch - GEM foil 2

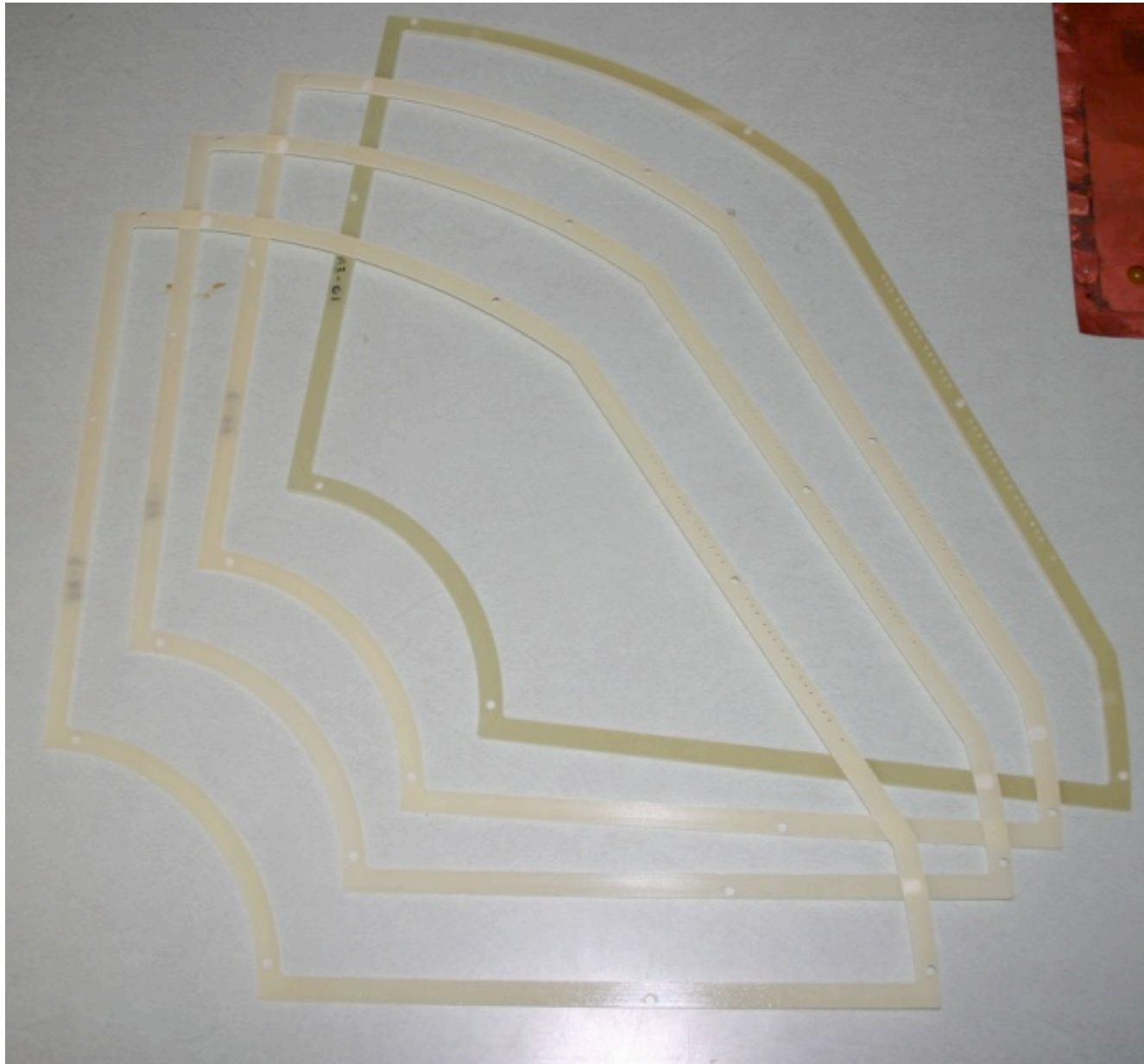
- mean pitch = 140 micron
- mean ID = 47 micron
- mean OD = 83 micron
- large difference ID - OD
 - explains HV to 700 V ?

CERN - GEM foil 2

- mean pitch = 140 microns
- mean ID = 53 micron
- mean OD = 66 microns
- speckling made measurement difficult

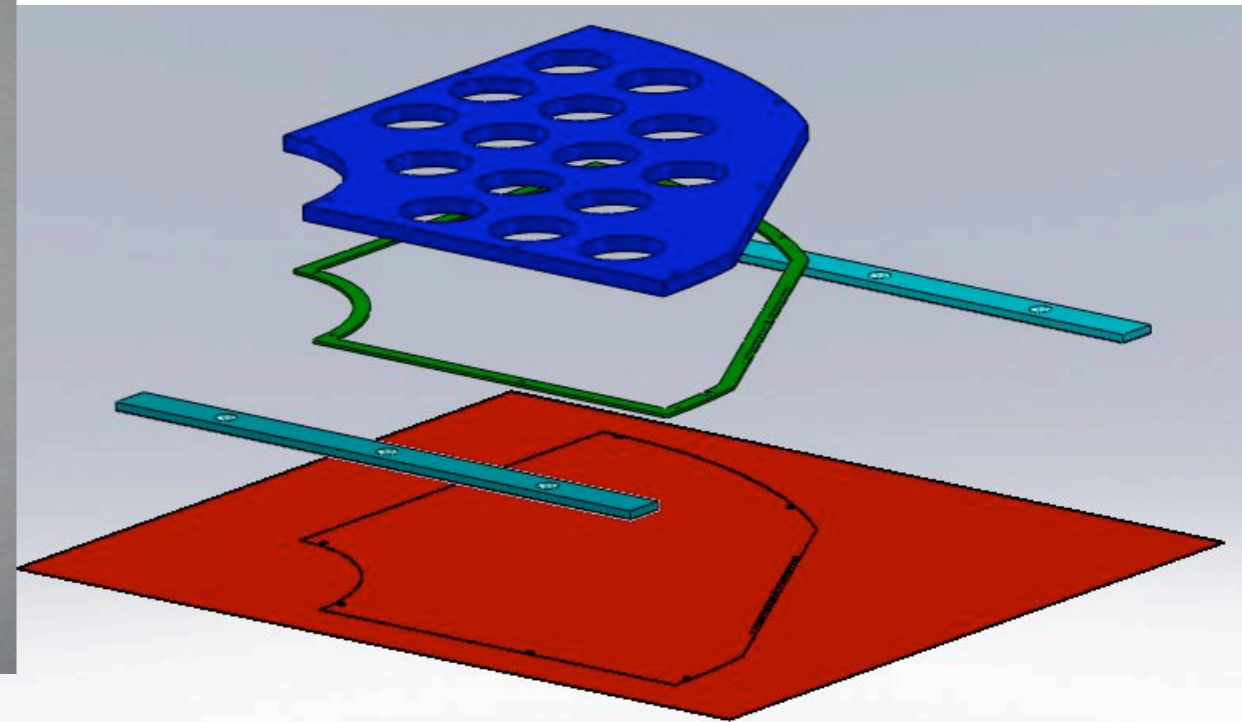


GEM Foil Stretching/Gluing - J. Bessuille (MIT)



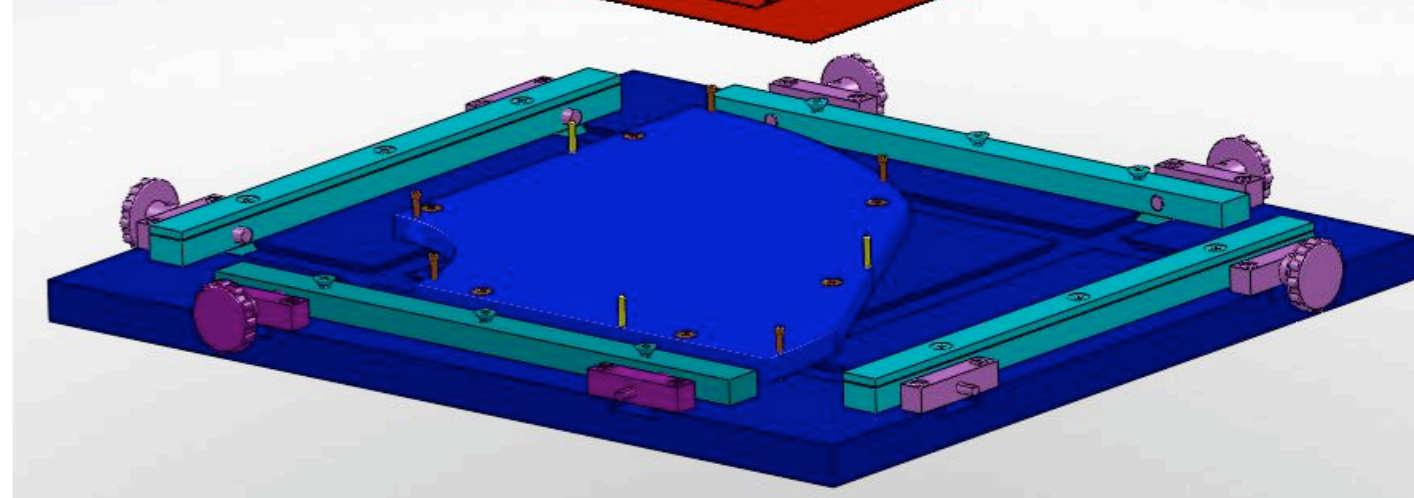
Pneumatic cylinders

- 50-60 psi →
- foil and frames aligned by 8 reference pins

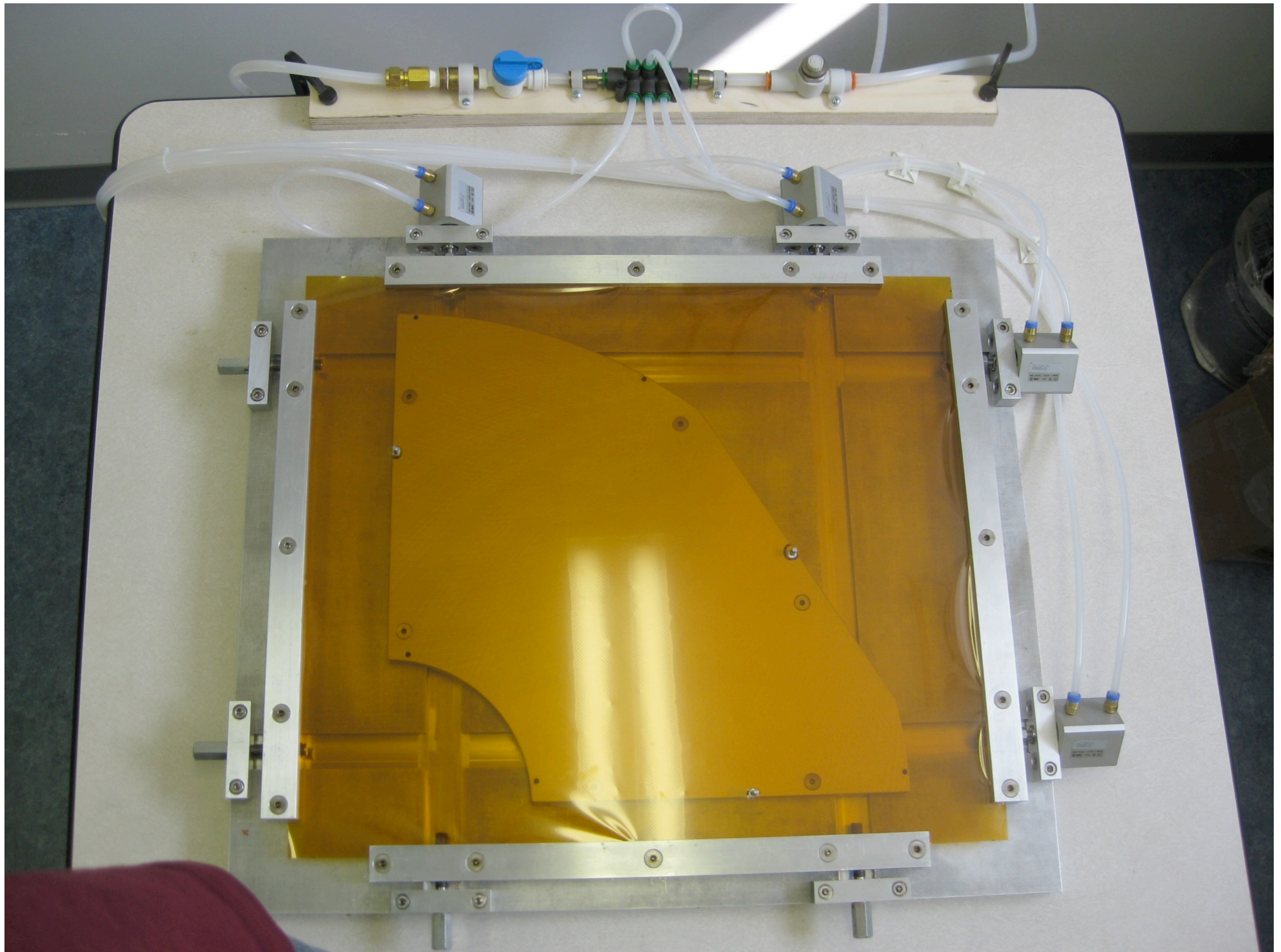


Deflection tests in progress

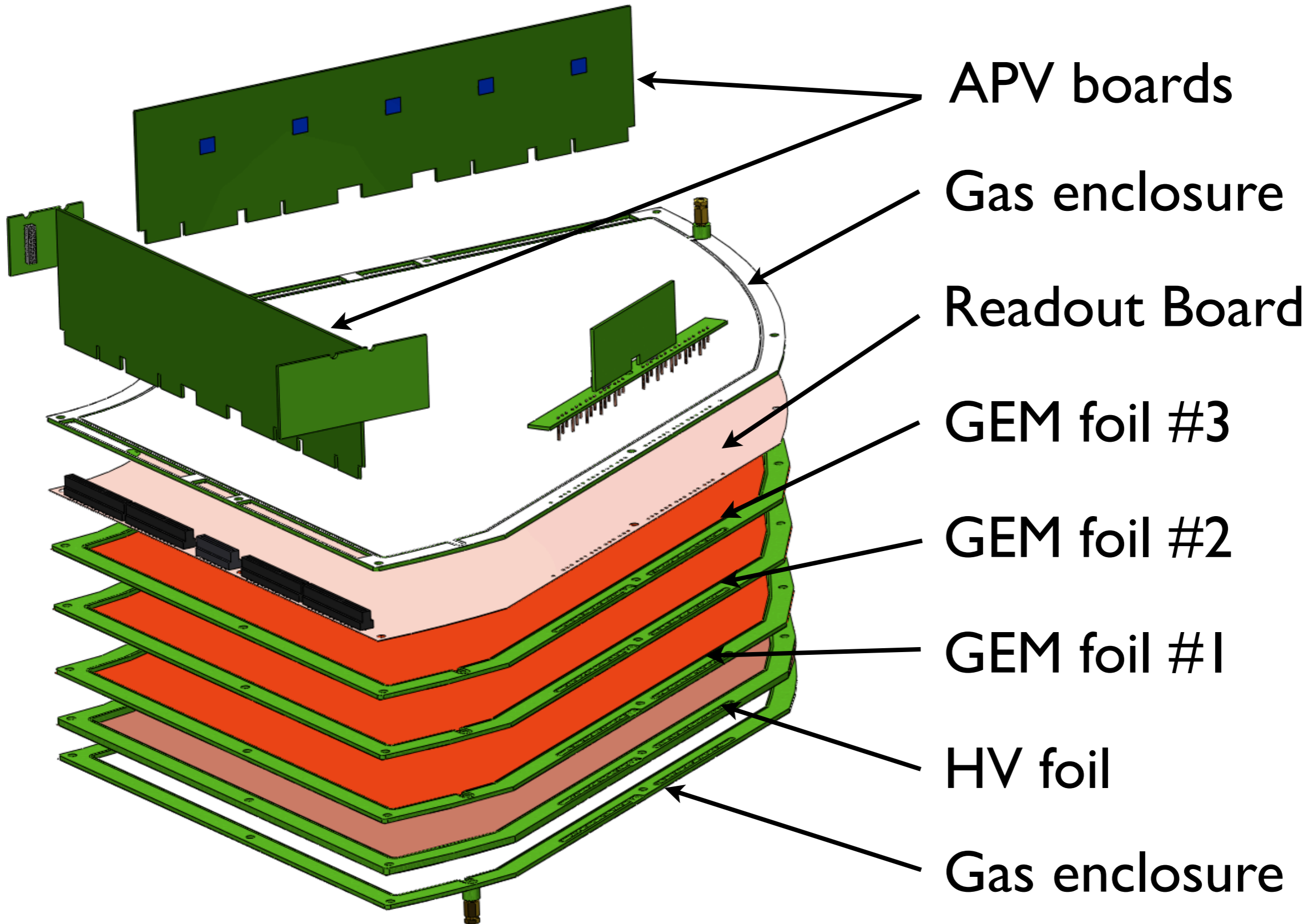
- slight delay due to accident !



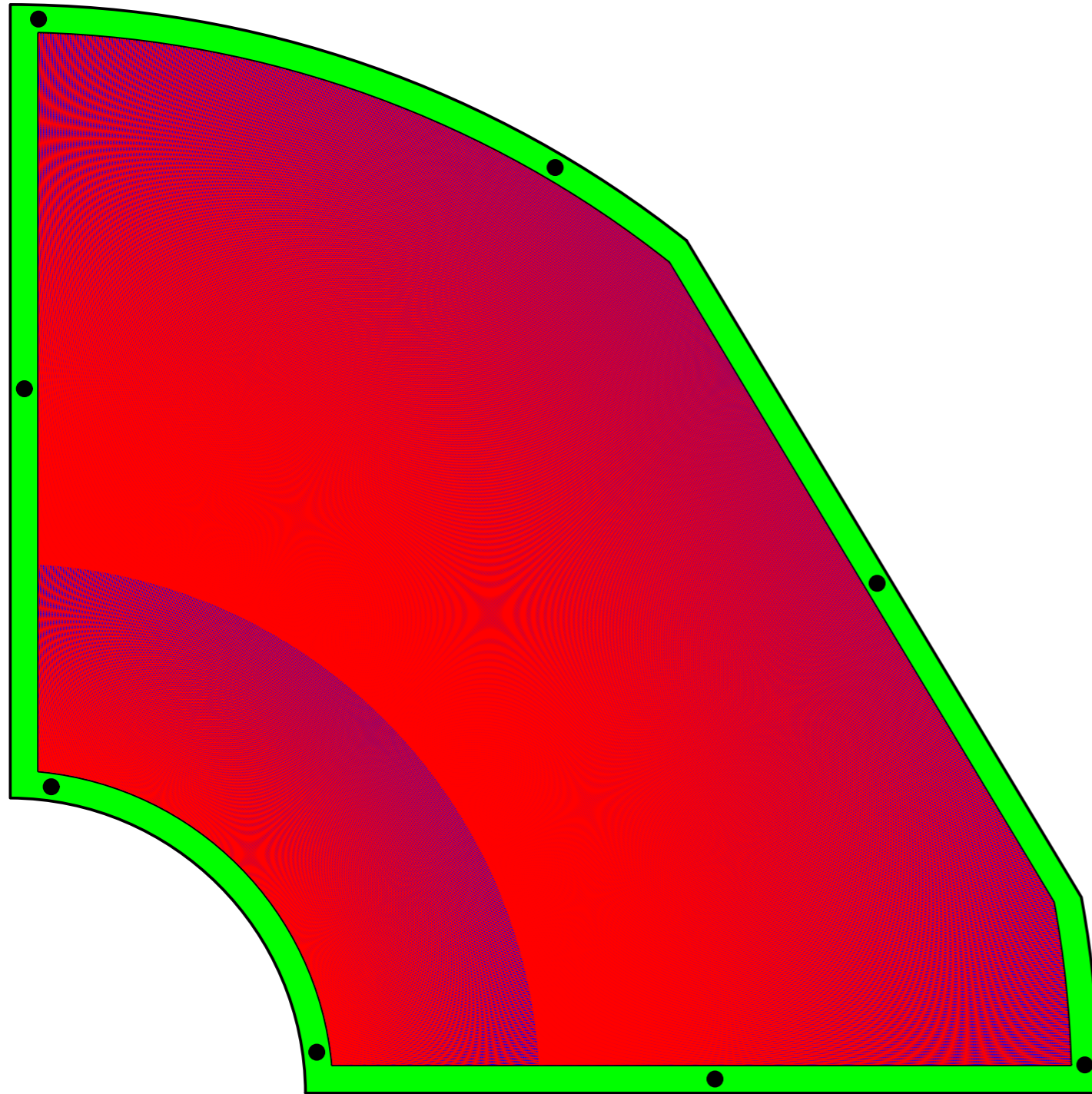
FGT GEM Foil Stretching/Gluing Fixture



FGT Triple GEM Quadrant



Preliminary 2D Readout Design



50 micron Kapton

- copper both sides
- laser etching exposes bottom layer
- Compunetics, Pittsburgh, PA

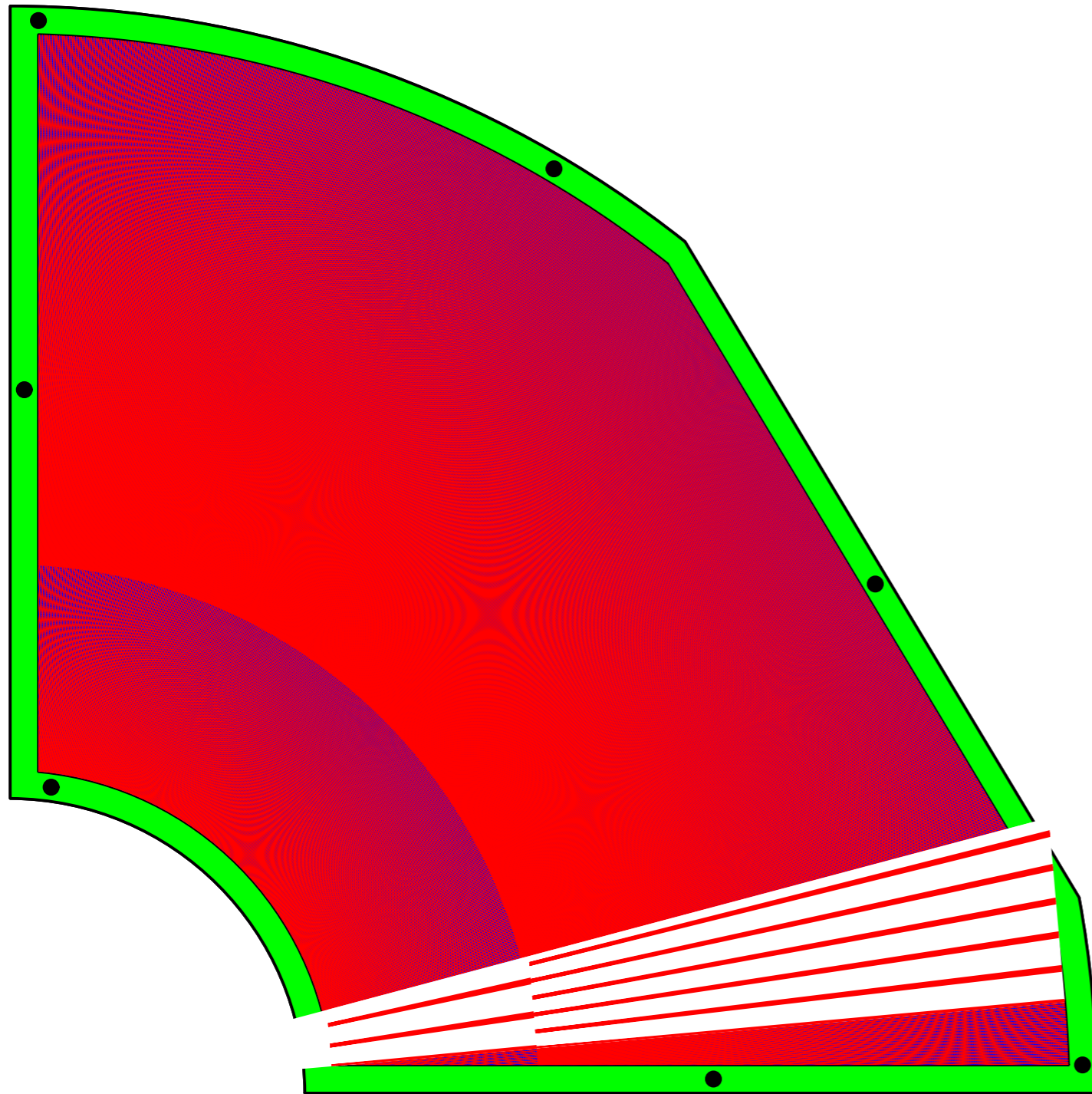
Top layer - Φ readout

- lines radiate from centre
- alternate lines end at $38.25/2$
- line width and pitch varies with radius
- line width 70 - 120 micron
- line pitch 300 - 600 micron

Bottom layer - R readout

- lines at constant radius
- line width 800 micron
- line pitch 900 micron

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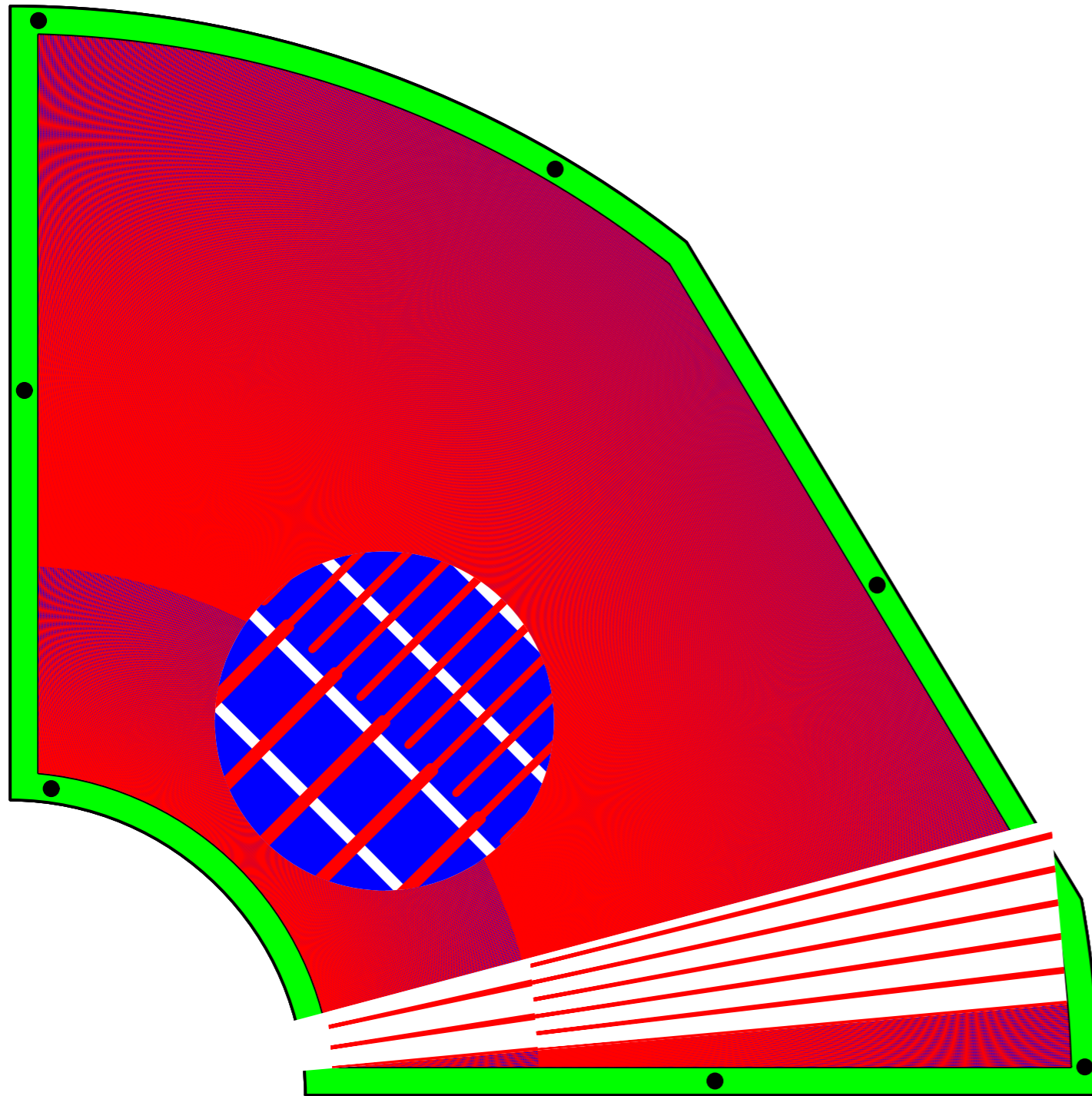
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Charge Sharing Calculations - R. Majka (Yale)

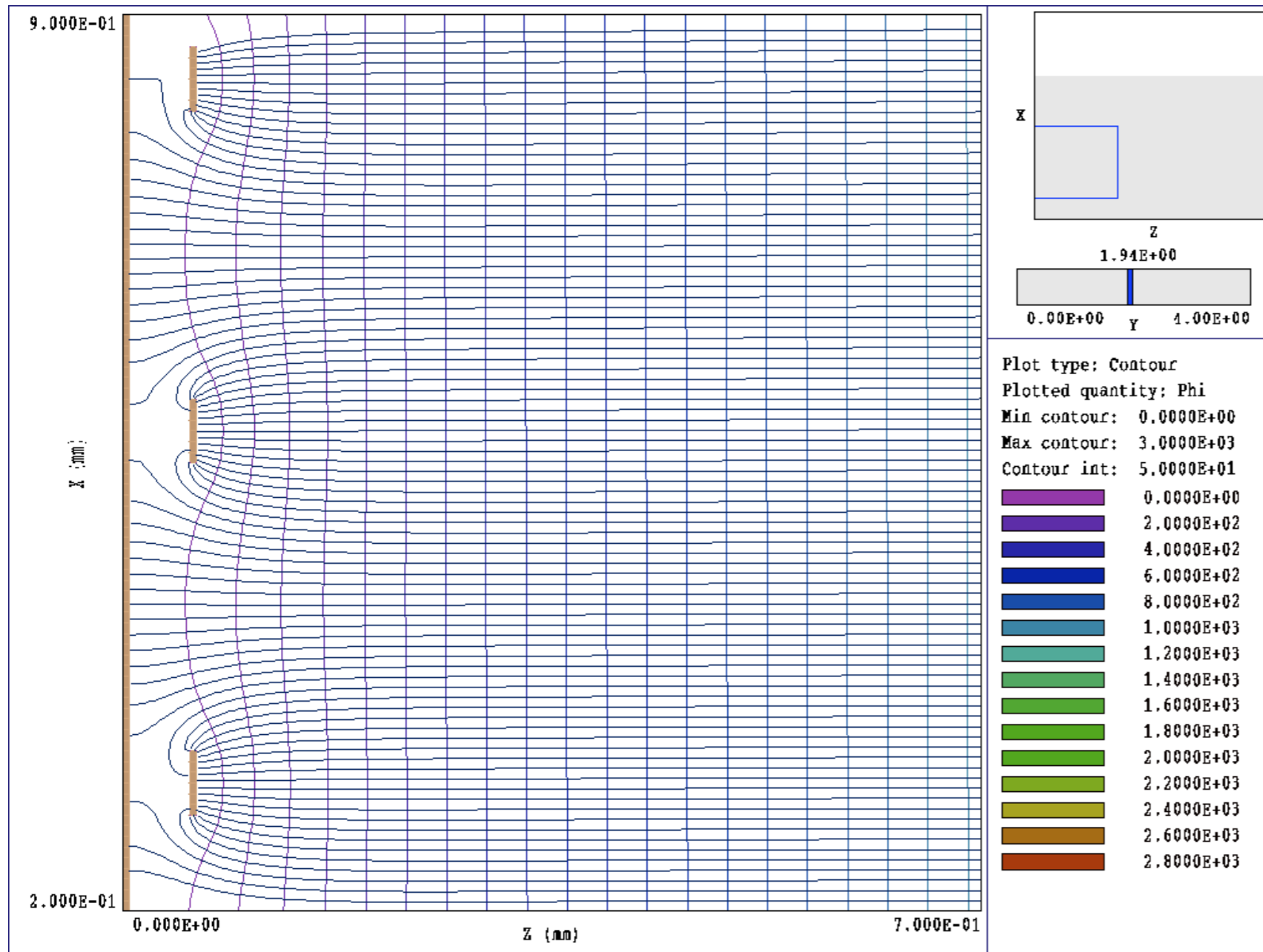
To resolve multiple hits need to know charge sharing ratio

- combination of line width and pitch for ~1:1 charge sharing

3D electrostatics calculations

- did not match results from previous detectors

Build charge sharing test



2D Charge Sharing Test Board

10x10 cm² test board

- test with ⁵⁵Fe source

Bottom layer

- uniform line width and pitch
 - 700 micron line width
 - 800 micron line pitch

Top layer

- 16 regions of different width and pitch

Pitch [μm]	Line width [μm]			
650	110	120	130	140
525	90	100	110	120
400	70	80	90	100
275	50	60	70	80

2D Charge Sharing Test Board

10x10 cm² test board

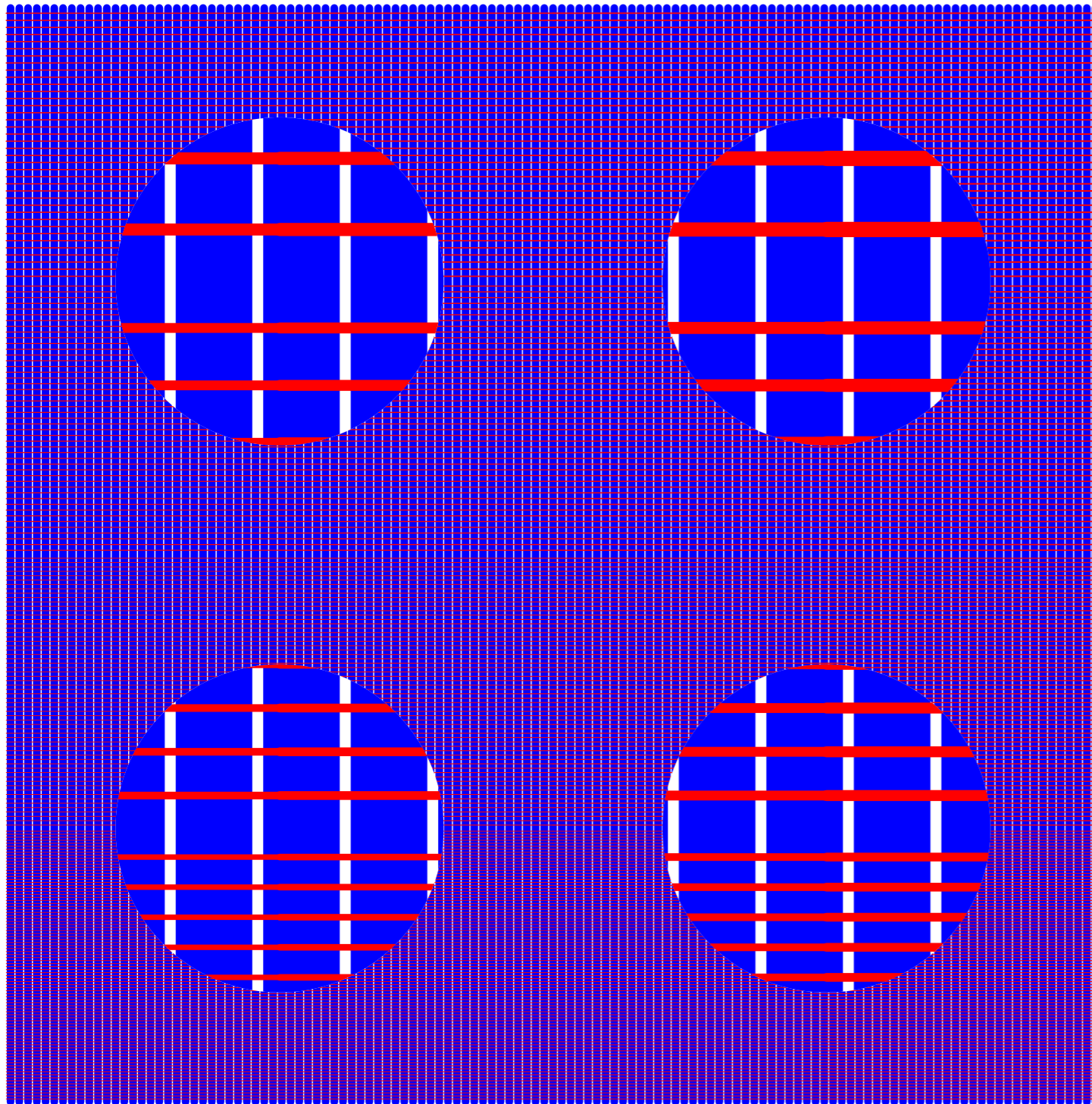
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400	70	80	90	100
275	50	60	70	80

Preliminary Charge Sharing - R. Majka (Yale)

Integrated charge on lines

- no individual line readout
- repeat test with line readout

line pitch / line width
measured calculated
ratio

275 / 50
2.16 1.22
1.77

275 / 60
2.46 1.38
1.79

275 / 70
2.69 1.67
1.61

275 / 80
2.75 1.85
1.48

400 / 70
1.60 0.81
1.97

400 / 80
1.55 0.92
1.69

400 / 90
1.68 1.03
1.63

400 / 100
1.80 1.20
1.49

525 / 90
1.26 0.65
1.94

525 / 100
1.21 0.74
1.65

525 / 110
1.30 0.83
1.56

525 / 120
1.36 0.83
1.63

650 / 110
0.95 0.57
1.67

650 / 120
0.91 0.65
1.41

650 / 130
0.96 0.67
1.44

650 / 140
1.01 0.68
1.48

APV25-S1 Readout Chip

Developed for CMS

- silicon strip detector
- used on GEMs by COMPASS

0.25 micron CMOS process

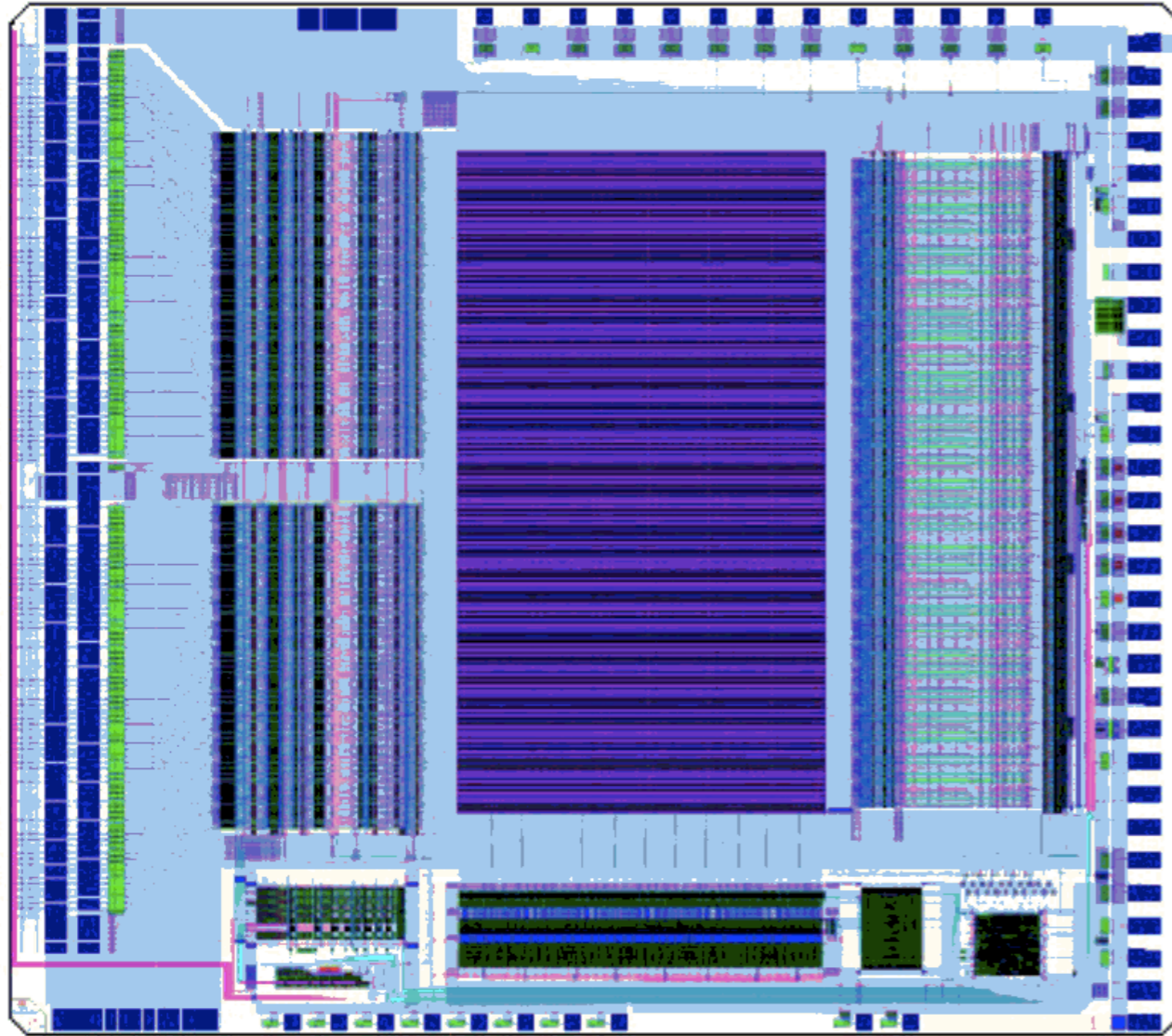
- 128 channels pre-amp/shaper
- 4 μs pipeline
- 40 MHz sampling rate

Power

- 194 mW / chip

Input double row of staggered pads

- pads $136 \times 58 \mu\text{m}$
- pitch 44 (88) μm



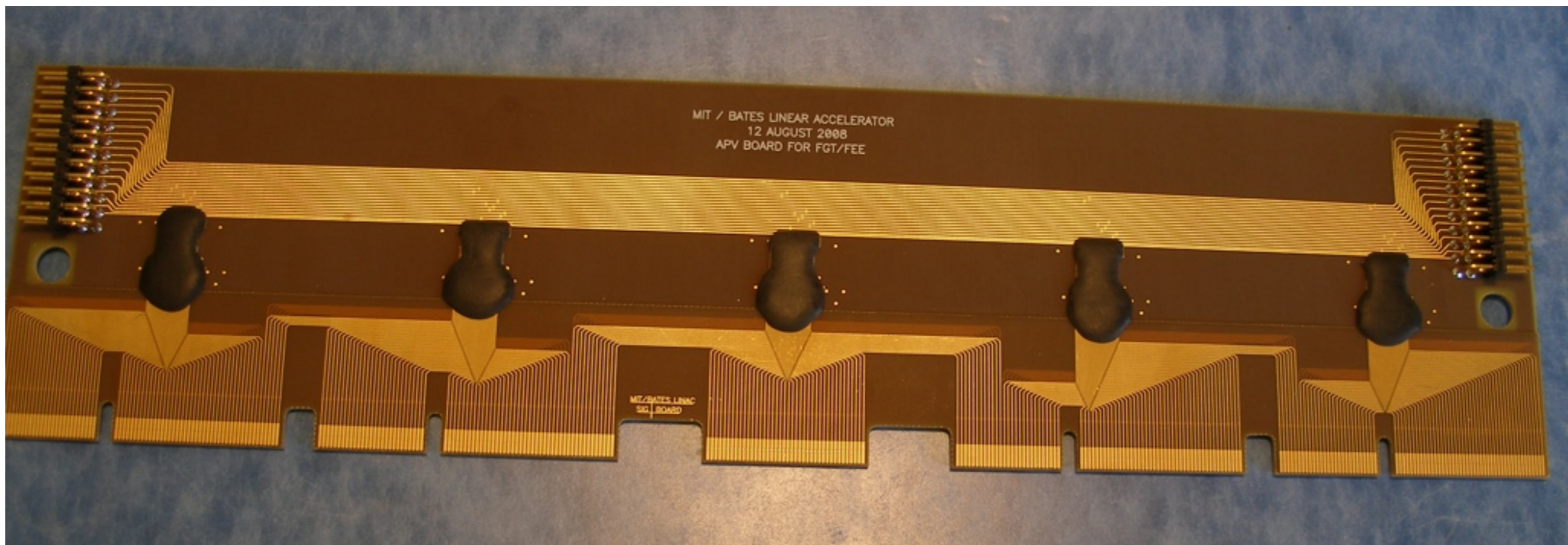
FGT APV Board - M. Plesko (MIT)

Fine pitch on APV inputs

- understandable for silicon strip detectors
- not well matched to typical GEM pitches

Several APV chips on board

- difficult to bond to normal PCB
- requires multiple layers with cut-outs
- expensive
- difficult to repair



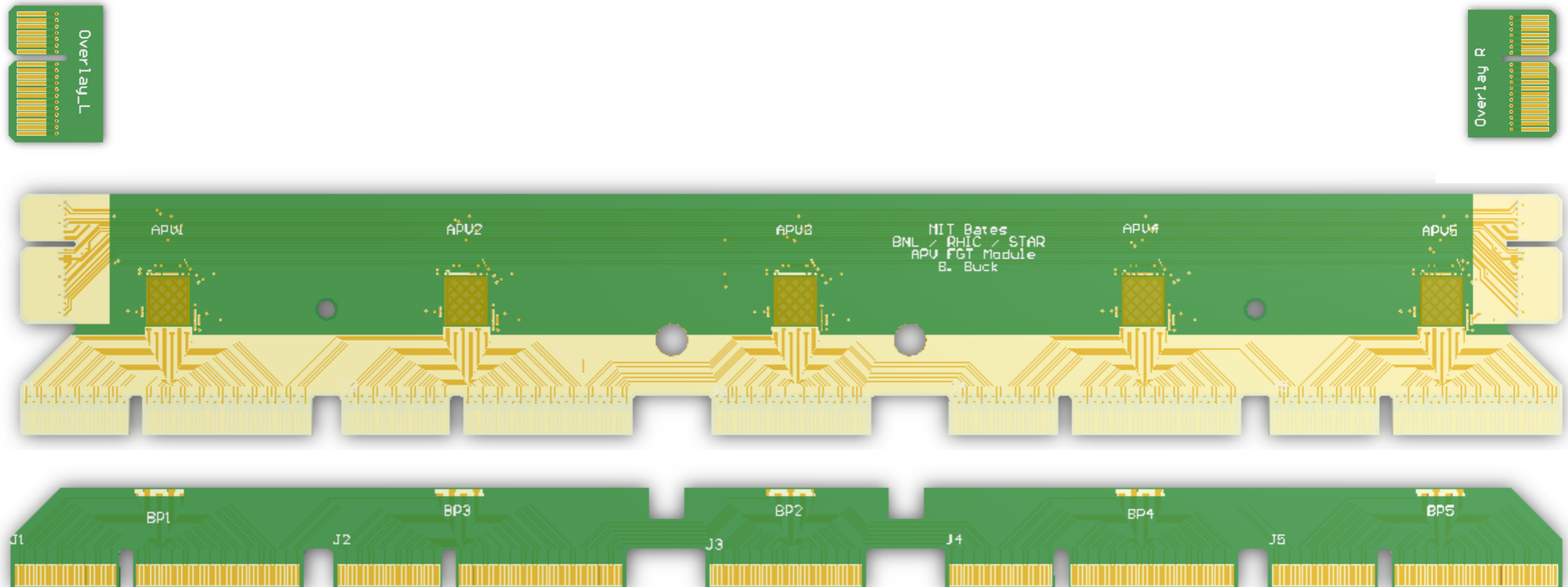
FGT APV Board - B. Buck (MIT), G. Visser (IUCF)

FGT design

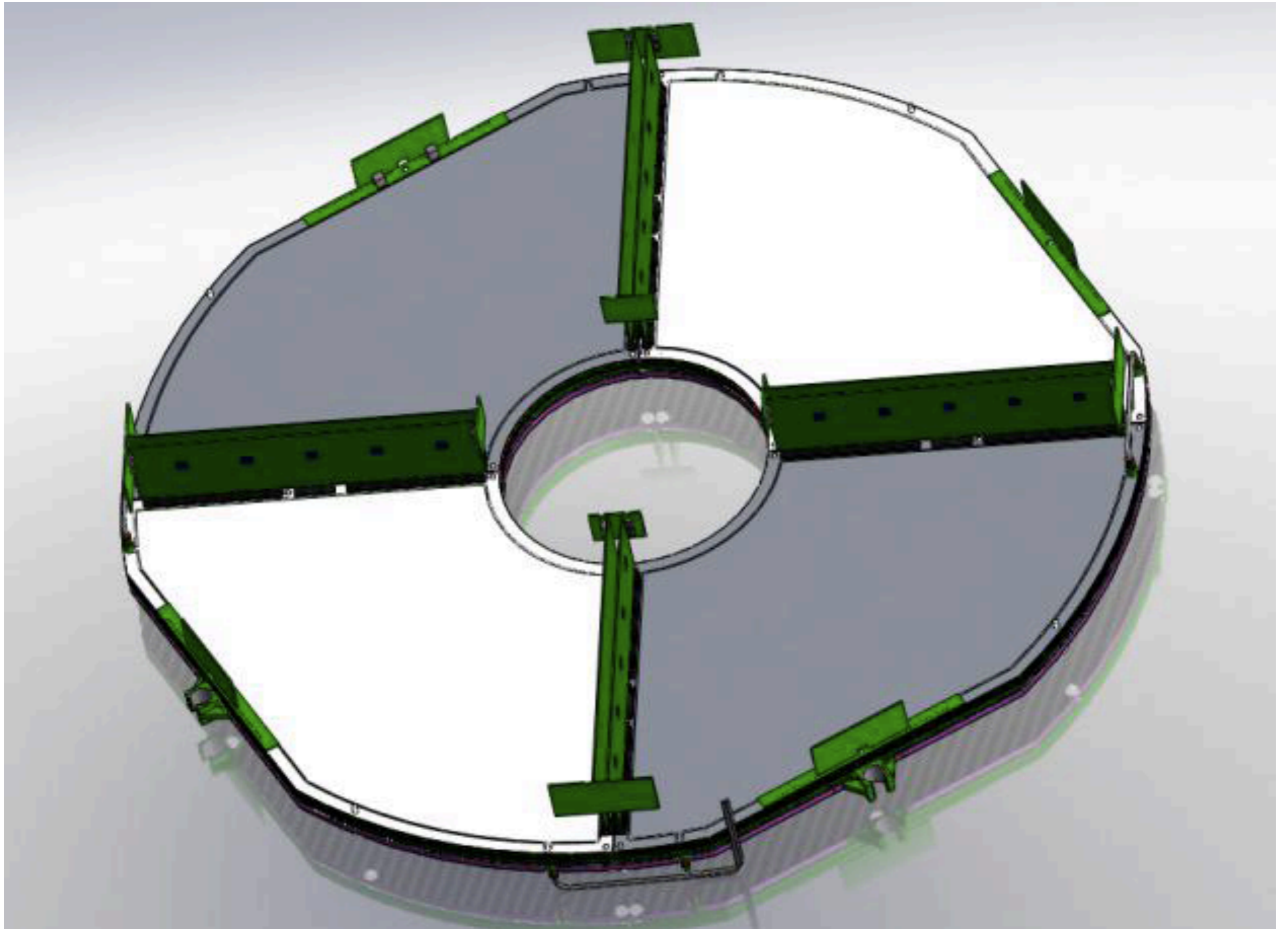
- 2 APV boards / quadrant
- 1 on each quadrant boundary
- pairs of APV boards connected and terminated together

New APV board

- assembly of 4 PCB
- slightly simpler design
- slightly cheaper
- still difficult to bond and repair



FGT Quadrant



Packaging APV Chips

Investigating packaging of APV chips

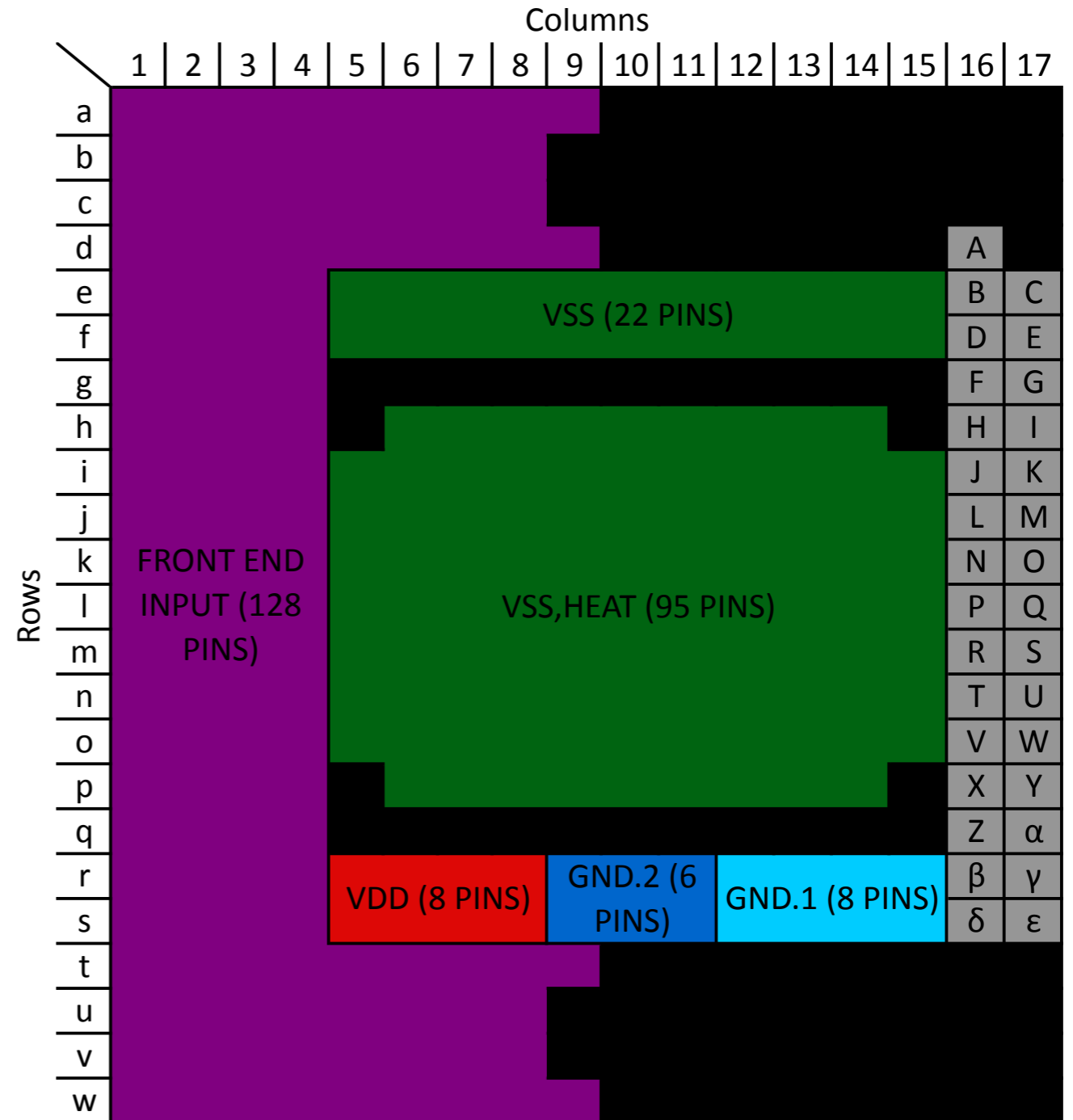
- Compunetics, Pittsburgh, PA
- First Level, York, PA

Simplify APV board

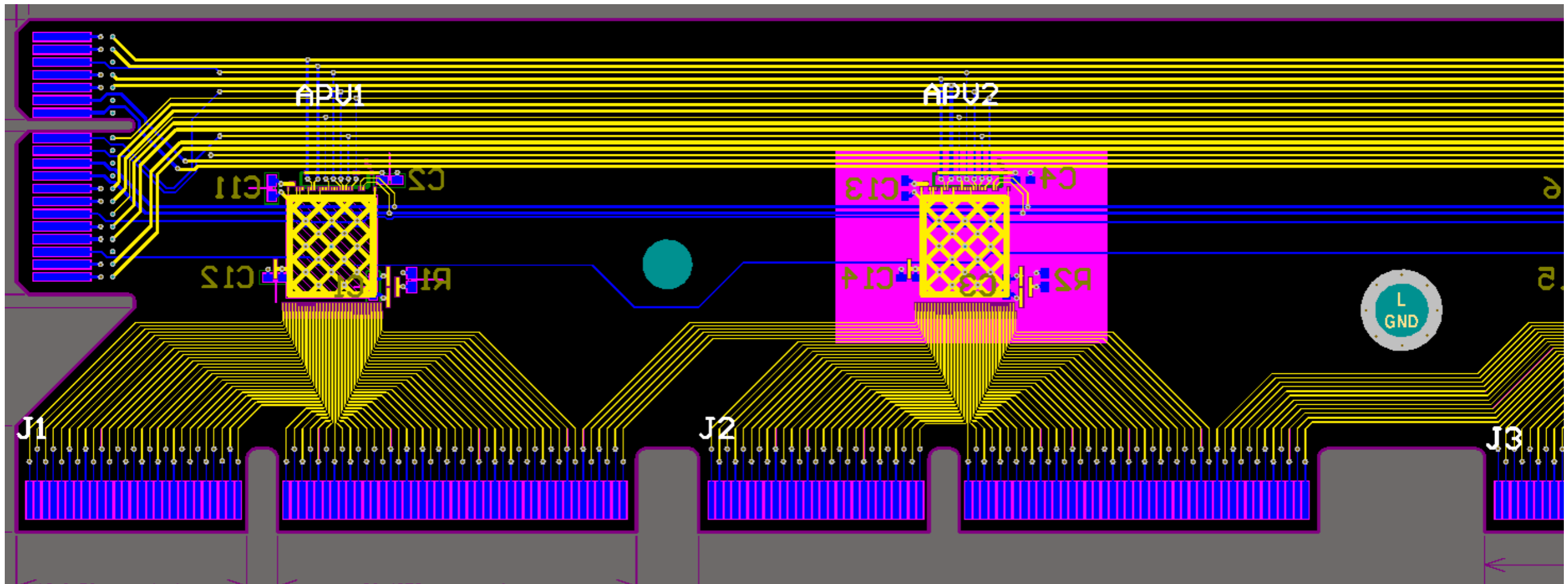
- normal PCB
- standard SM technology
- possible to replace packages

Ball Grid Array

- 23x17 rectangular package
- 0.8 mm pitch between pins
- package 20 x 15.2 mm²
- multiple pins for power
- heat sink
- still iterating on design / pin-out



APV Board with 23x17 BGA



Forward GEM Tracking Upgrade for STAR

Future

- production of GEM foils with Tech-Etch seems to be well in-hand
 - improved dark currents with cleaning (R. de Oliveira)
 - glass masks to address hole offset and stripped pattern
- still have a number of tests to conduct and details to finalise
 - charge sharing with individual line readout → finalise 2D readout design
 - deflection of GEM foils → tension or need for spacers
- APV boards
 - have existing solution using complicated board and bonding directly to board
 - but packaging of APV chips could simplify design and reduce cost

Schedule

- production to start early 2010
- expect to complete in ~6 months after start
- test quadrants with source, cosmics, and real STAR readout system
- install in STAR summer 2011

Thank you